

SC3: Session 3A\_14  
Jul. 8, 2015 9:40-10:00

✘  
Optical Kerr switching and comb generation in  
a silica whispering gallery mode microcavity

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# Outline

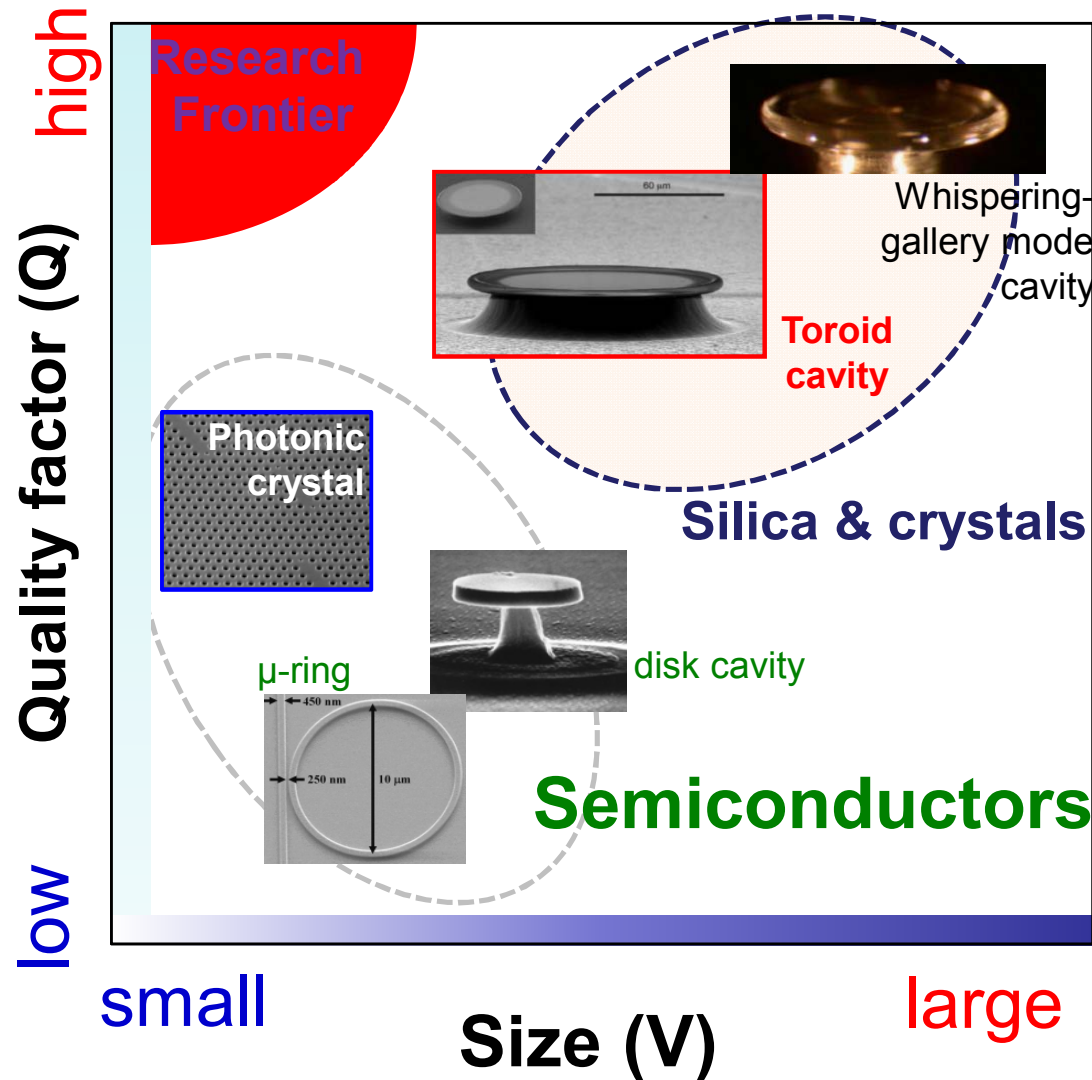


- 1. Background  
(photonic crystal and WGM cavity)**
- 2. Kerr switch w/ WGM cavity**
- 3. Kerr comb w/ WGM cavity**
- 4. Summary**



# Various high Q microcavities

## ▶ Various microcavities



## ▶ Quality factor and mode volume

### ◆ Q-factor

$$Q = \omega \times \frac{\text{stored energy}}{\text{power in/out}}$$

### ◆ Photon density

$$\propto \frac{Q}{V}$$

## ▶ Applications

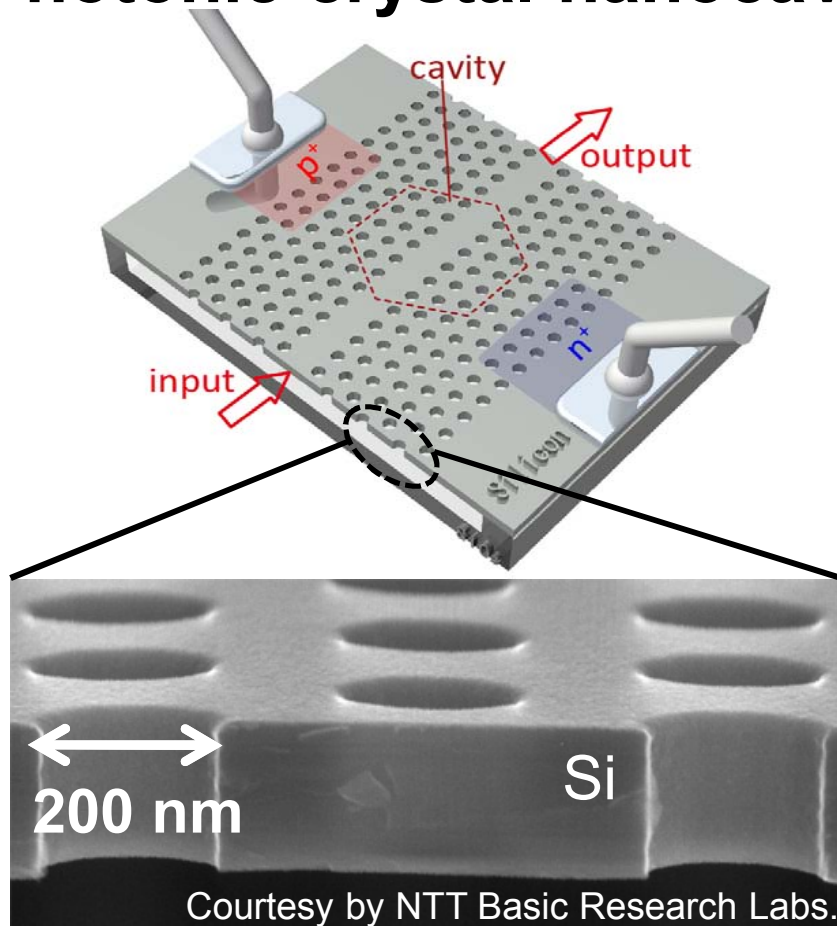
- ▶ All-optical switching
- ▶ Optical buffer
- ▶ Cavity QED devices
- ▶ Low-threshold lasers
- ▶ Optical sensors
- ▶ Optical frequency combs



# High Q/V microcavities

**Microcavity = A device that cage photons**

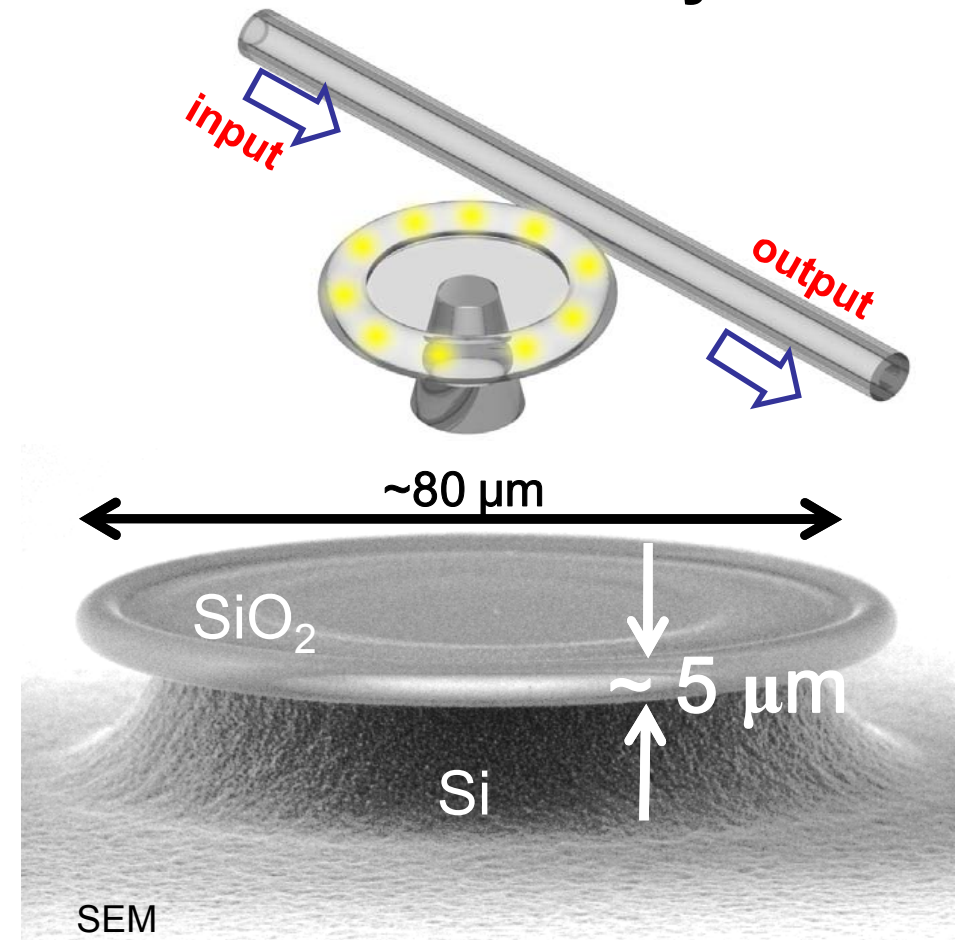
## ► Photonic crystal nanocavity



$$V = 1.5 (\lambda/n)^3$$

$$Q = 10^6$$

## ► WGM microcavity



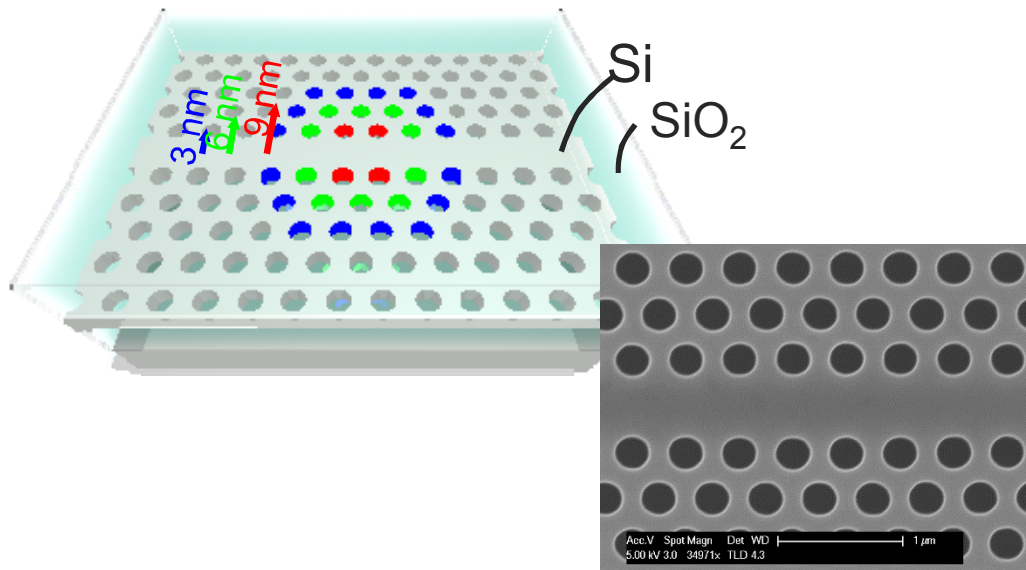
$$V = >100 (\lambda/n)^3$$

$$Q = 10^8$$



# Photonic crystal nanocavity

## ▶ Small size and high-Q



Very high  $Q = 1.2 \times 10^6$

T. Tanabe, *et al.* Nature Photon. **1**, 49 (2007).

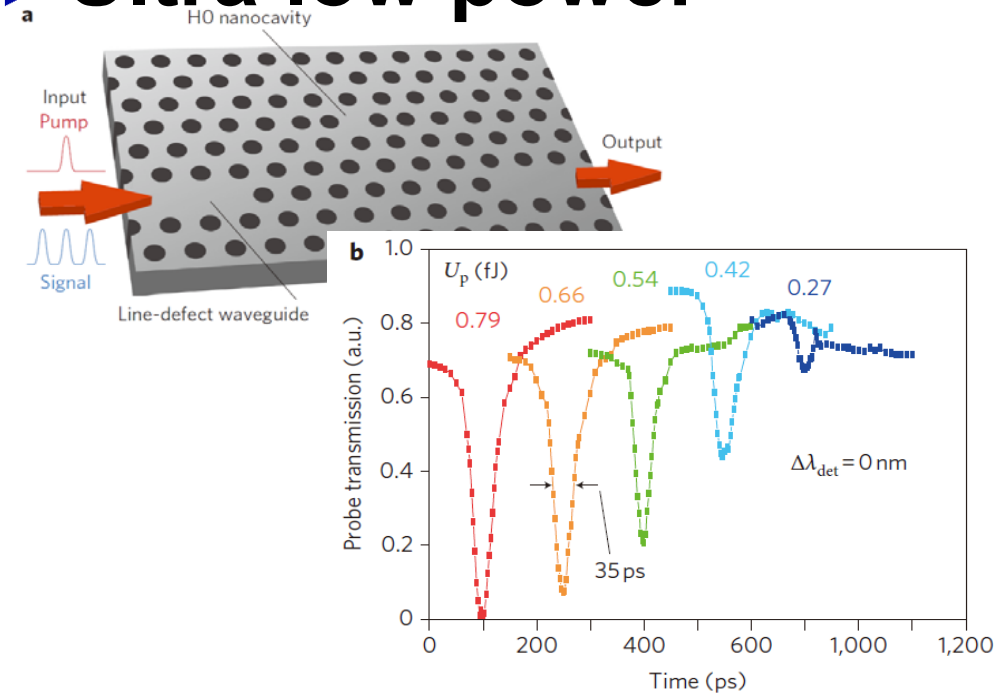
Highest  $Q$  w/ CMOS process & structure

Y. Ooka, *et al.*, Sci. Rep. **5**, 11312 (2015).

High coupling w/ fiber

T. Tetsumto, *et al.*, Opt. Express **23**, 16256 (2015).

## ▶ Ultra low power



Carrier based 100-fJ switch in Si

T. Tanabe, *et al.*, APL 90 031115 (2007).

Carrier based 0.66-fJ switch in InGaAsP

K. Nozaki, *et al.*, Nature Photon. **4** 477 (2010).

Towards all-optical logic gates

A. Fushimi, *et al.*, Opt. Express **22** 4466 (2014)

# Motivation



## ▶ Si based PhC

😊 **Refractive index: 3.4**

→ Small size

😞 **Loss: 1 dB/cm**

→  $Q = 10^6$  is possible

😞 **Band gap: @1.2  $\mu\text{m}$**

→ Carrier effect

(absorb photons)

## ▶ SiO<sub>2</sub> based WGM

😞 **Refractive index: 1.45**

→ Large size

😊 **Loss: 0.13 dB/km**

→  $Q > 10^8$  is possible

😊 **Band gap: @ 140 nm**

→ Kerr effect

(operation w/o absorption)

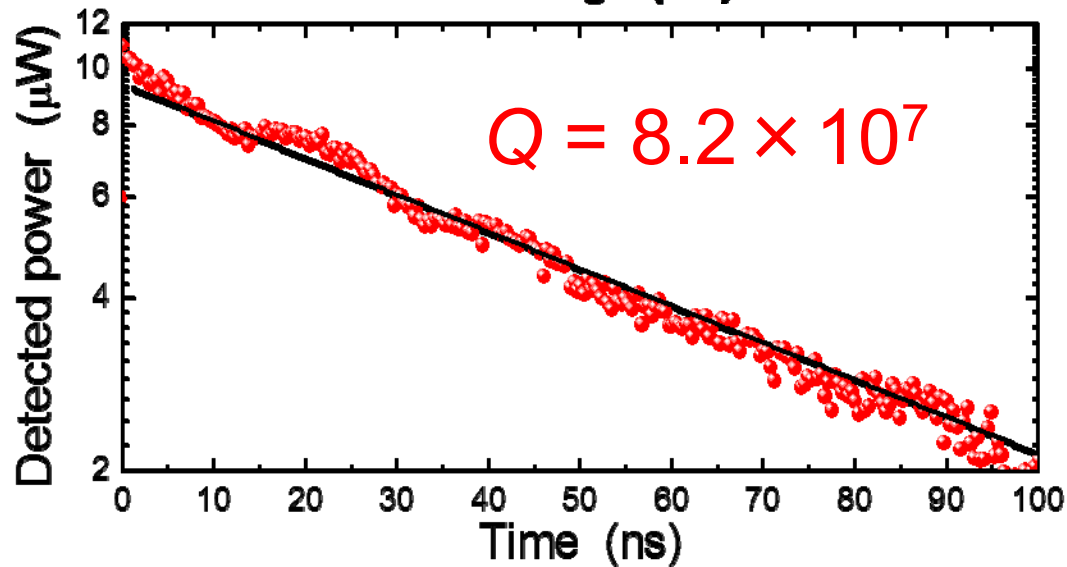
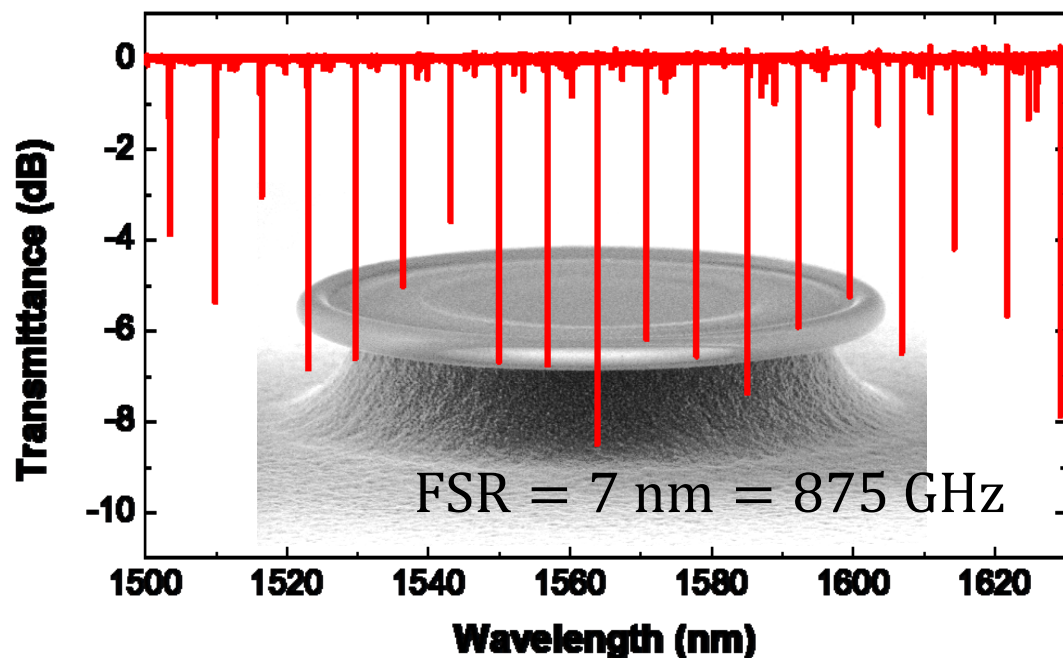
## *Motivation*

1. Is Kerr switch feasible at reasonable power
2. What is the minimum possible power w/ Kerr switch.

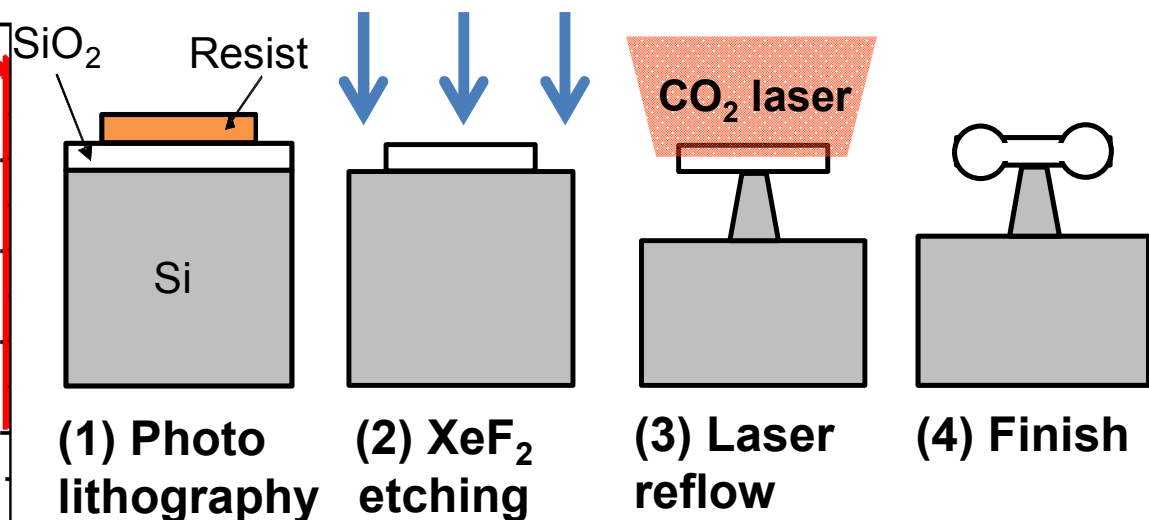
# Ultra-high Q toroidal microcavity



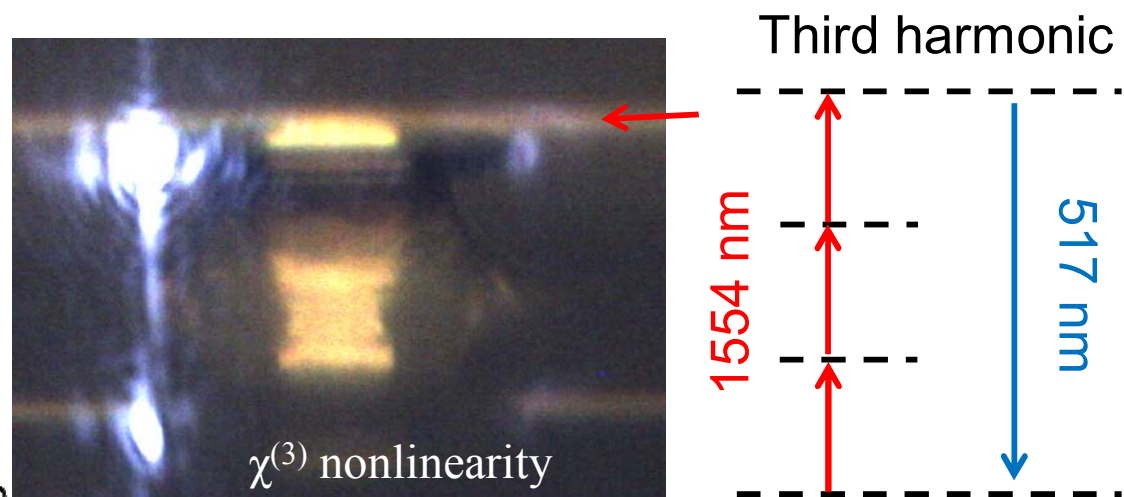
## ► Spectrum & photon lifetime



## ► Fabrication



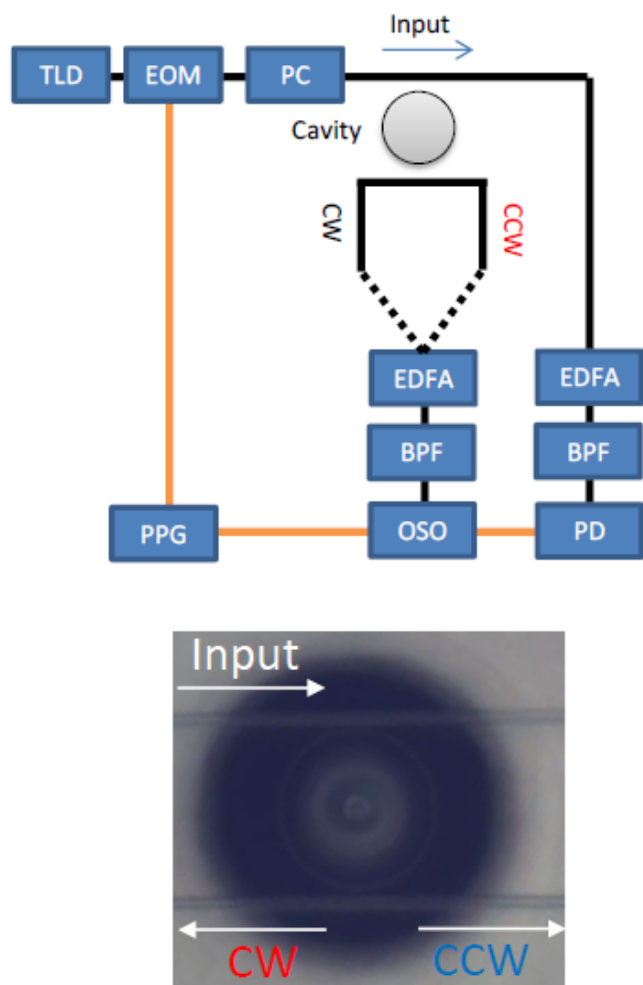
## ► White light generation (Kerr effect)



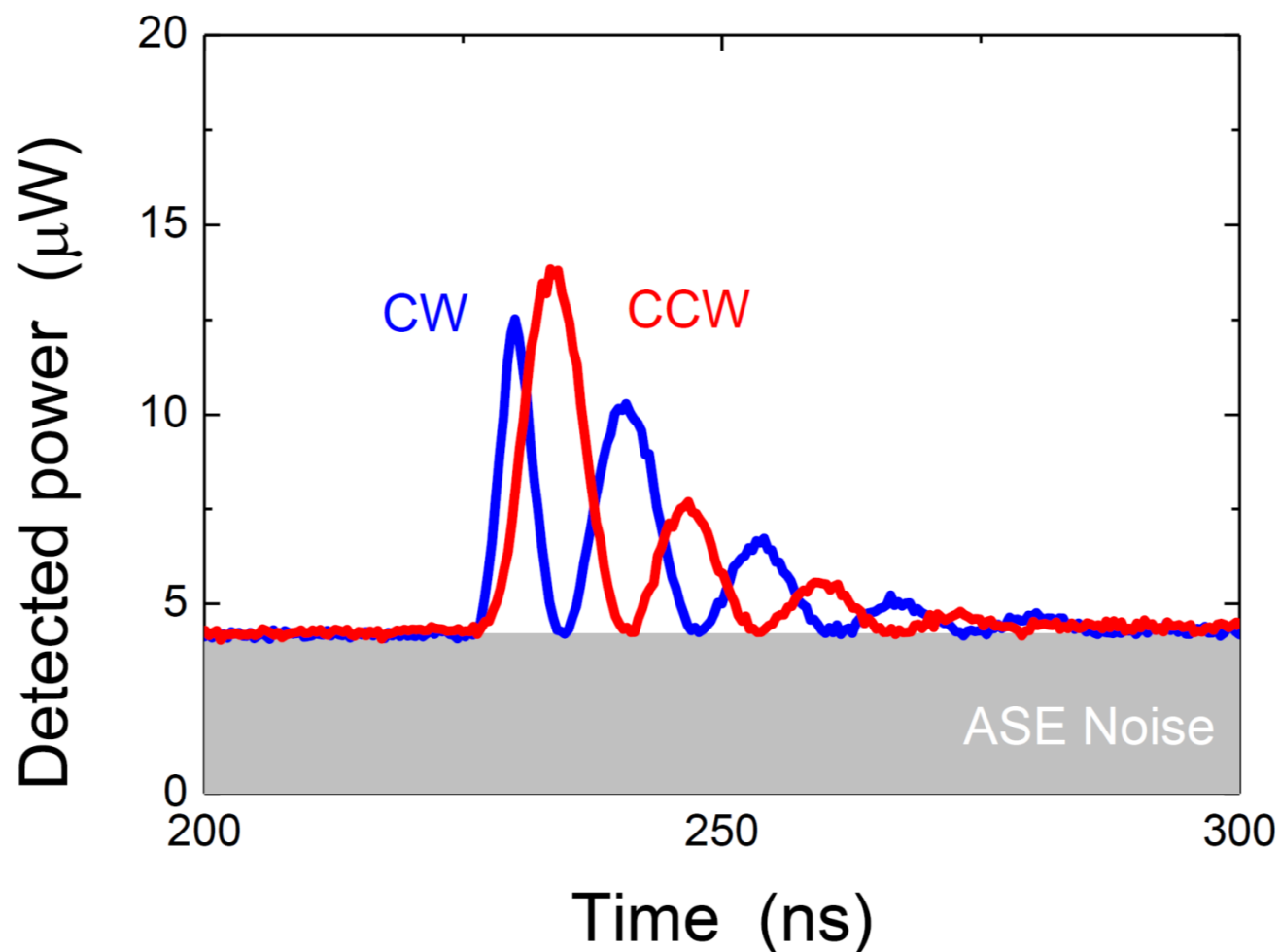
## Time domain measurement: Rabi oscillation



### ► Experimental setup



### ► Waveform



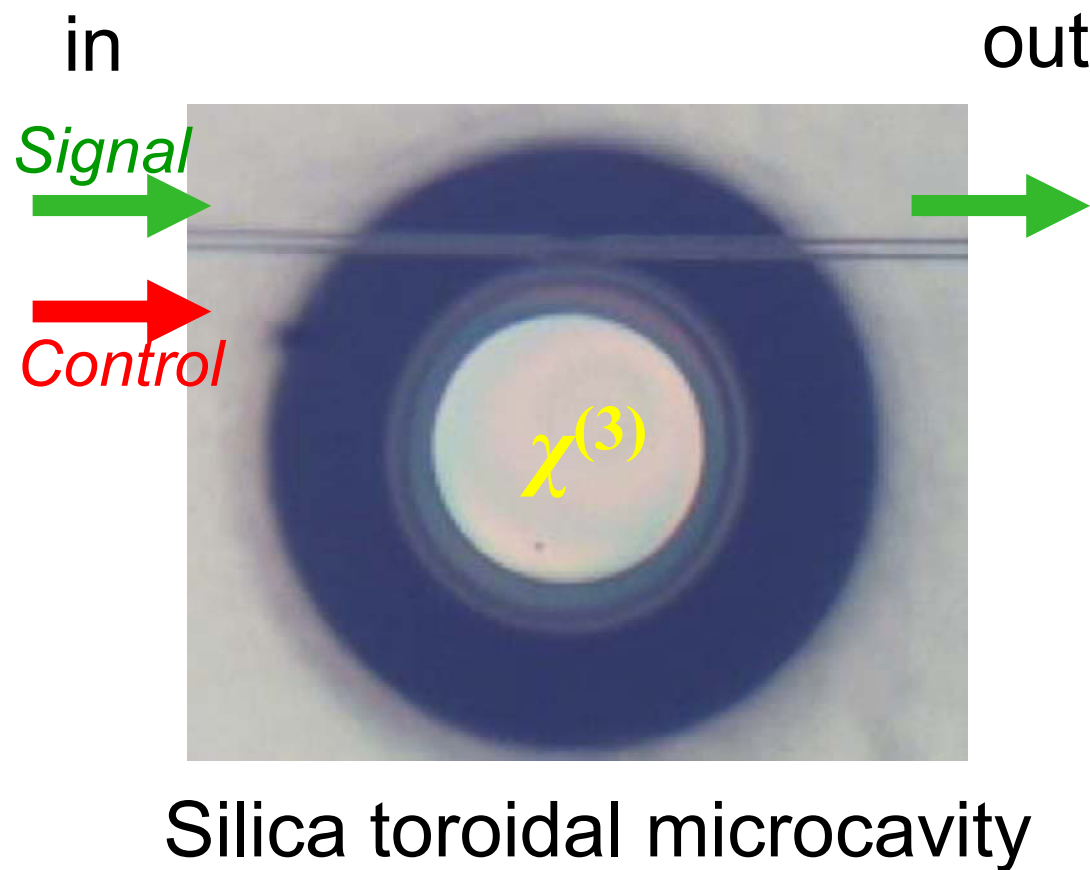


# All optical switch (Silica / Kerr effect)

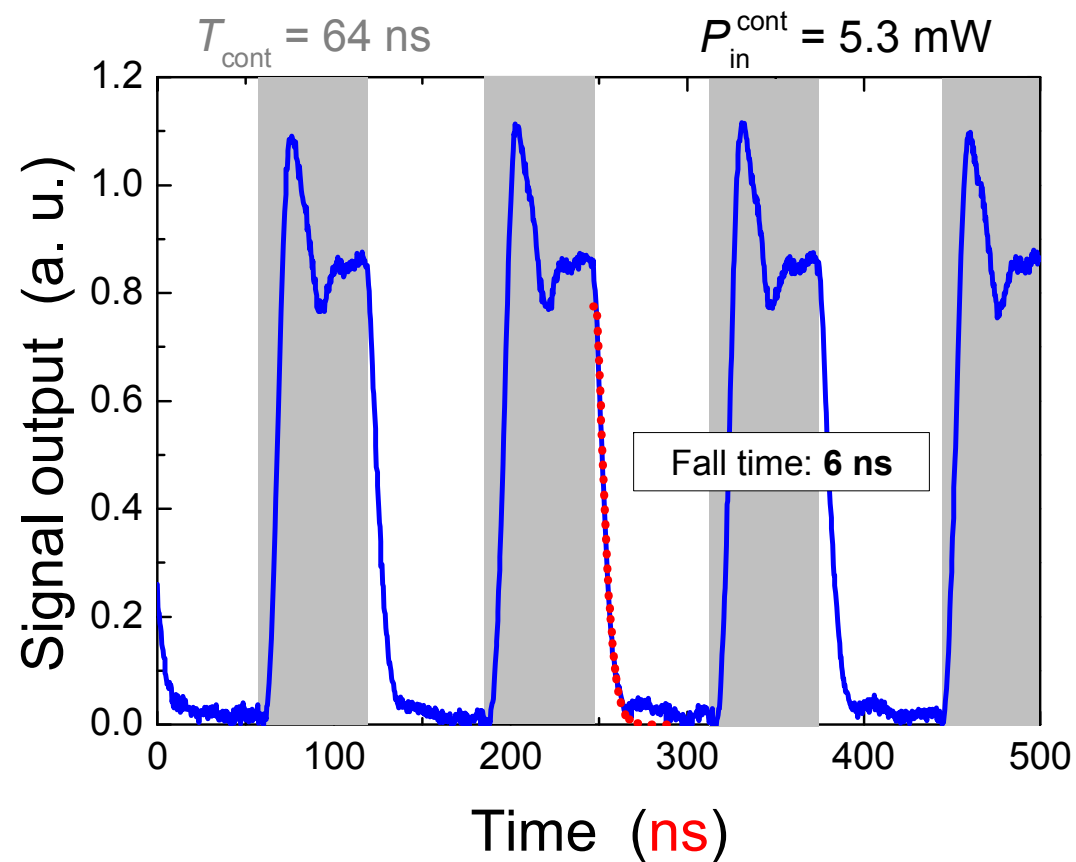


W. Yoshiki and T. Tanabe, Opt. Express **22**, 24332 (2014).

## ▶ WGM microcavity device



## ▶ Low power Kerr switch



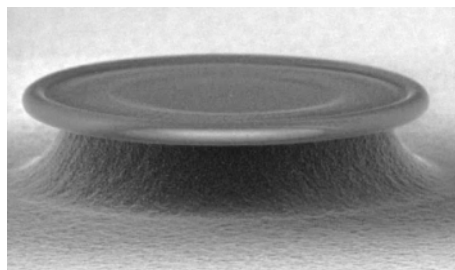
**Modulation observed at 36  $\mu\text{W}$**

# Comparison w/ other Kerr switches

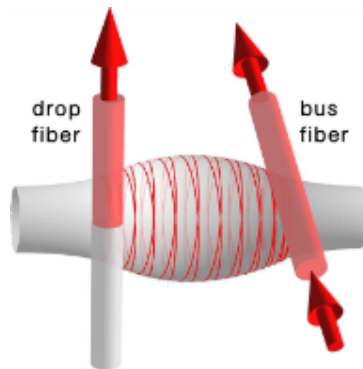


W. Yoshiki and T. Tanabe, Opt. Express **22**, 24332 (2014).

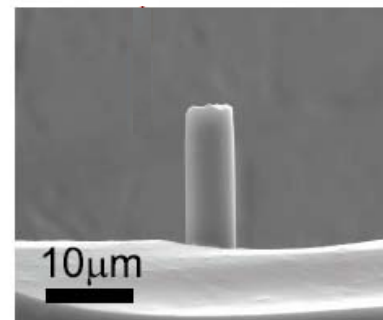
**Silica toroid**



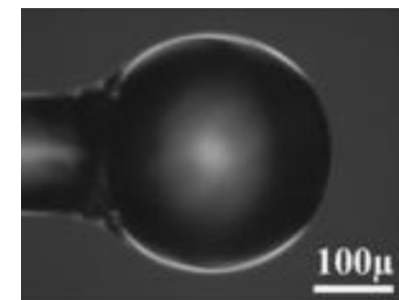
**Silica bottle**<sup>1)</sup>



**a-Si:H cylinder**<sup>2)</sup>



**Silica sphere w/ polymer coat**



**Material**

**Silica**

**Silica**

a-Si:H

Silica + Polymer

**Power**

**36 μW**

50 μW

5 mW

1.5 kW

**On chip**

**Yes**

No

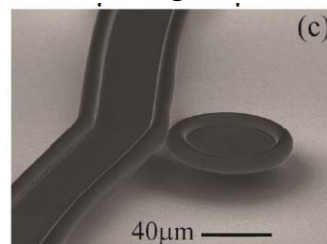
No

No

Packaging w/ polymers<sup>4)</sup>



Integration w/ waveguides<sup>5)</sup>



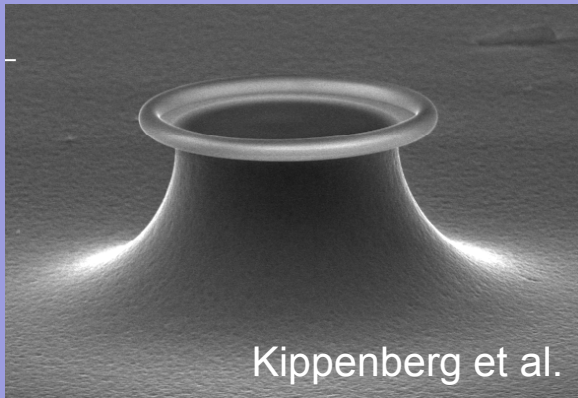
- 1) M. Pöllinger & A. Rauschenbeutel, Opt. Express 18, 17764– (2010)
- 2) N. Vukovic et al., Sci. Rep. 3, 2885-(2013).
- 3) I. Razdolskiy et al., Opt. Express 19, 9523- (2011).
- 4) X. Zhang & A. Armani, Opt. Express 21, 23592- (2013)
- 5) F. Monifi et al., IEEE Photon. Technol. Lett. 25, 1458- (2013)



# Kerr comb

## Kerr comb

### Microcavity

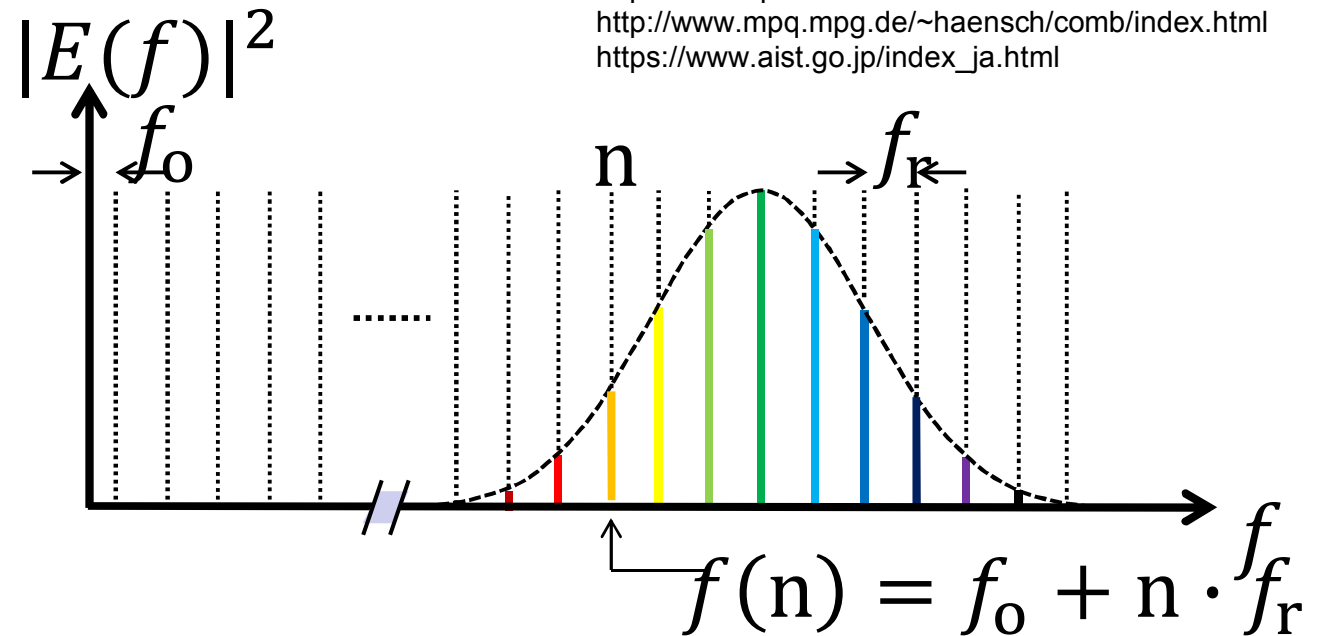


- ✓ On chip
- ✓ High repetition rate  
(10GHz-1THz)
- ✓ Low cost
- ✓ Low pump threshold

Threshold pump power of degenerate four-wave mixing

$$P_{threshold} \propto \frac{V}{Q^2}$$

$V$  : mode volume,  $Q$  : quality factor



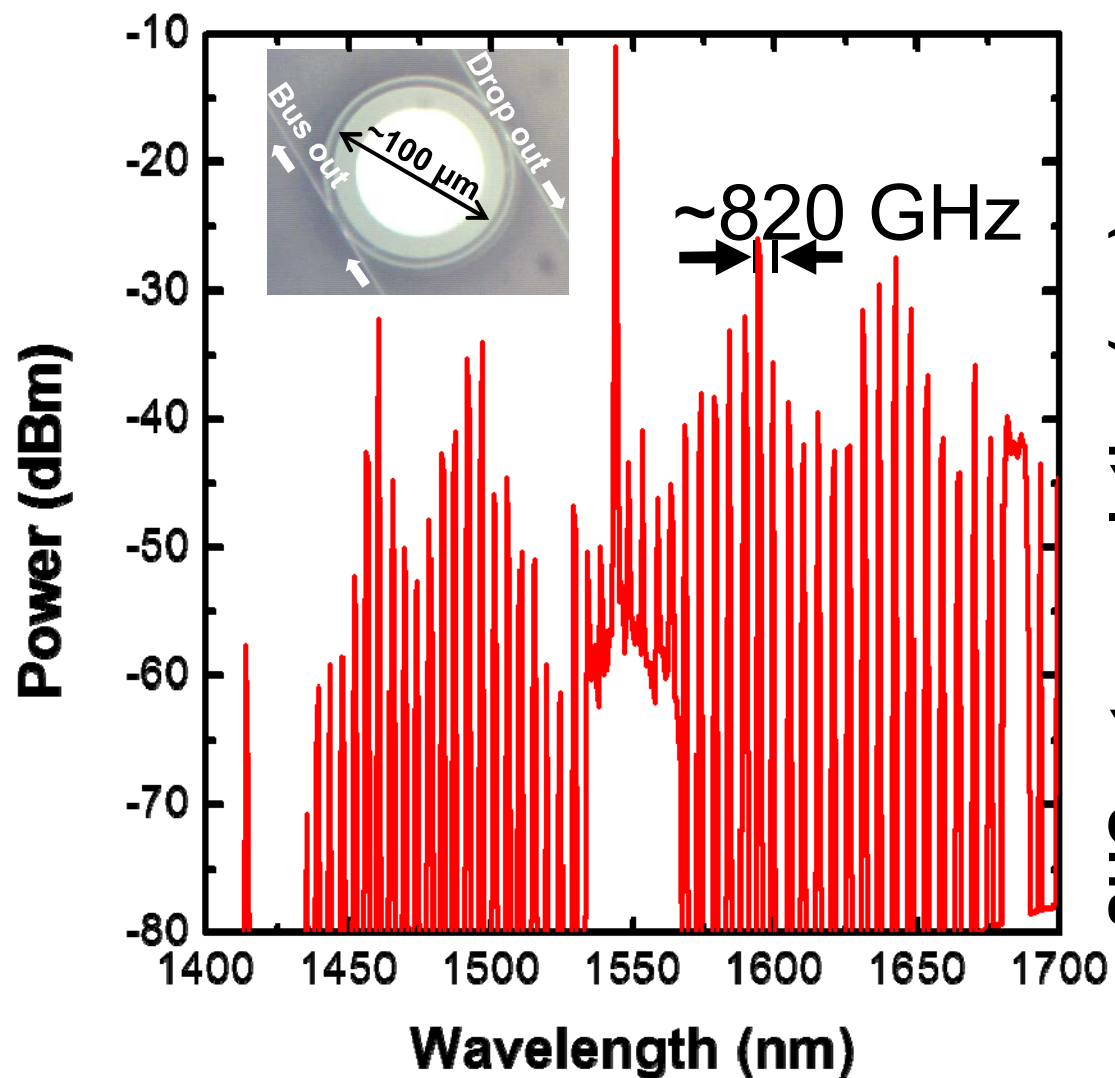
Kerr comb has been demonstrated, but still, the following must be solved:

- 1) Dispersion management w/ high Q cavity
- 2) The mechanism on mode-locking in microcavities is still not fully understood

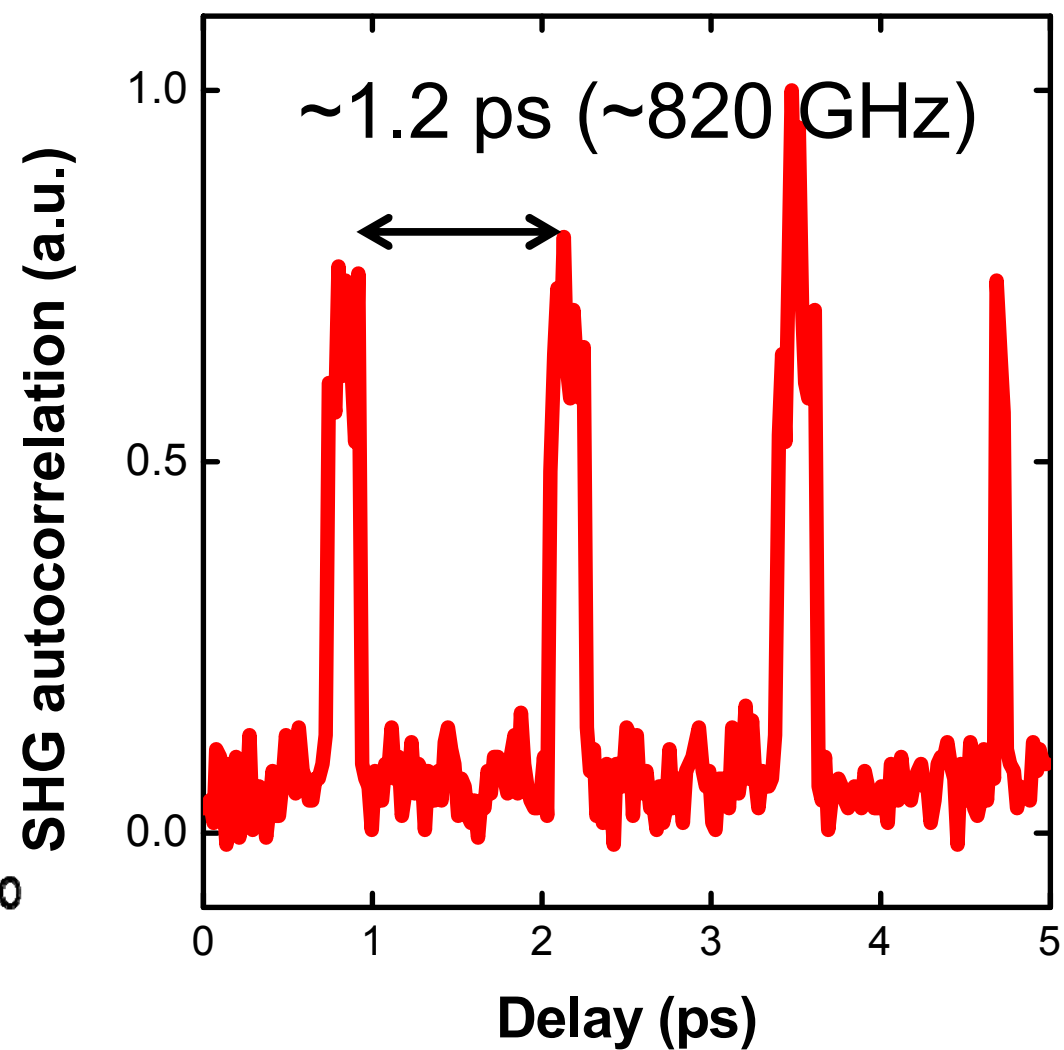
## Ultrahigh repetition rate pulse generation



## ► Kerr comb generation



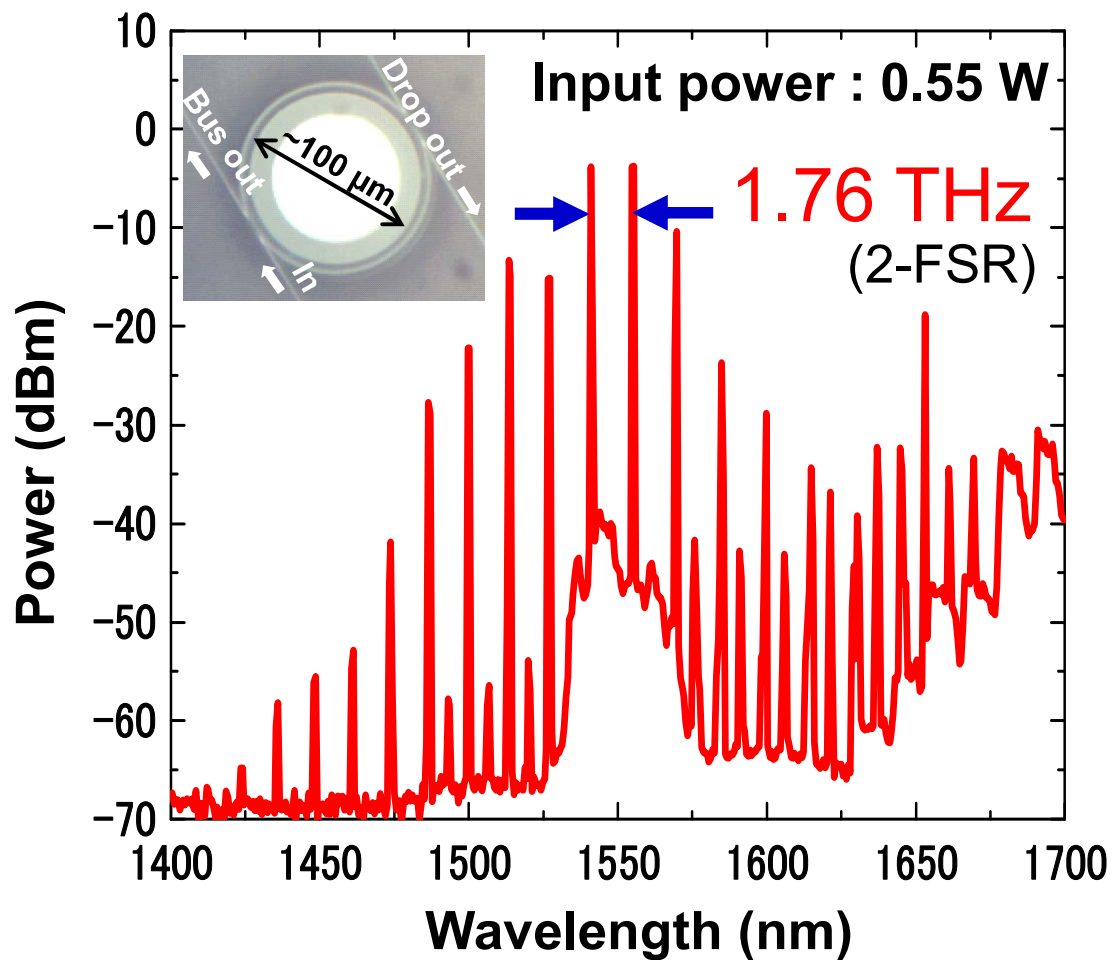
## ► SHG autocorrelation trace



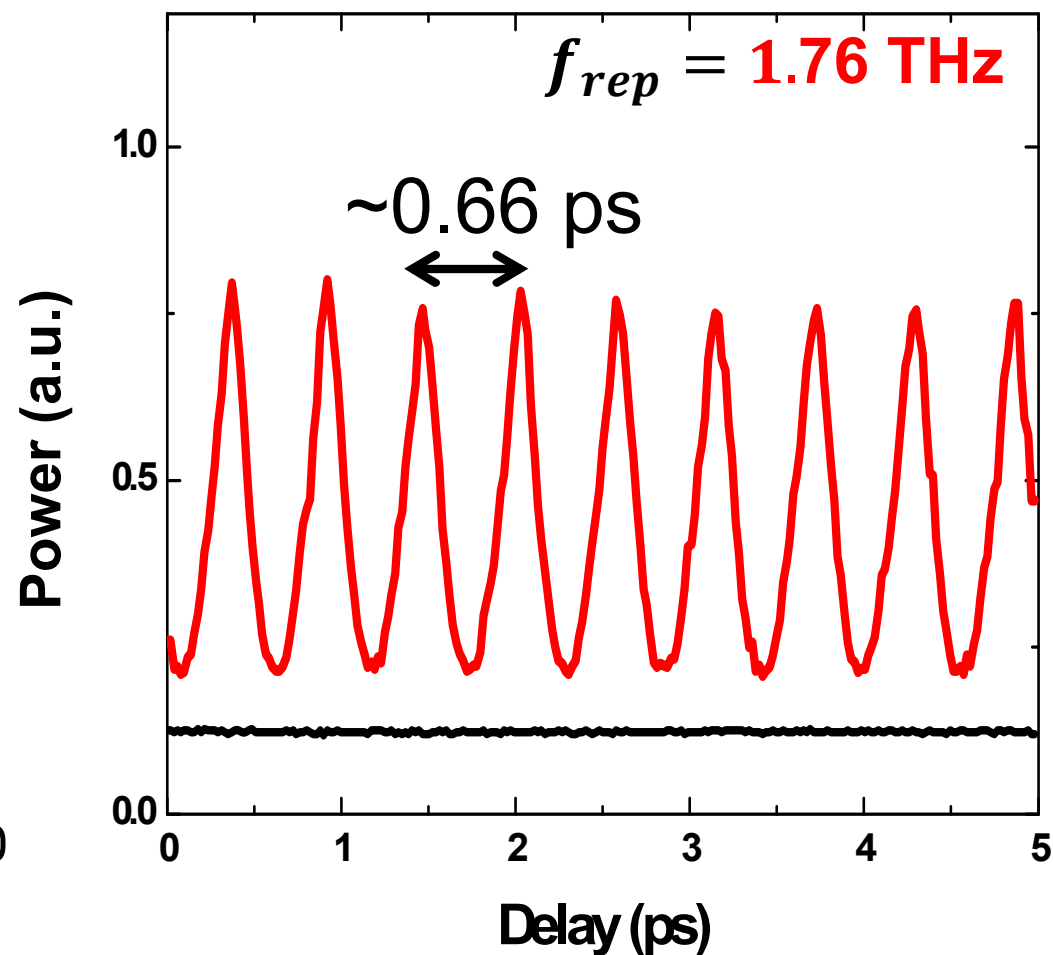
# Ultrahigh repetition rate pulse generation



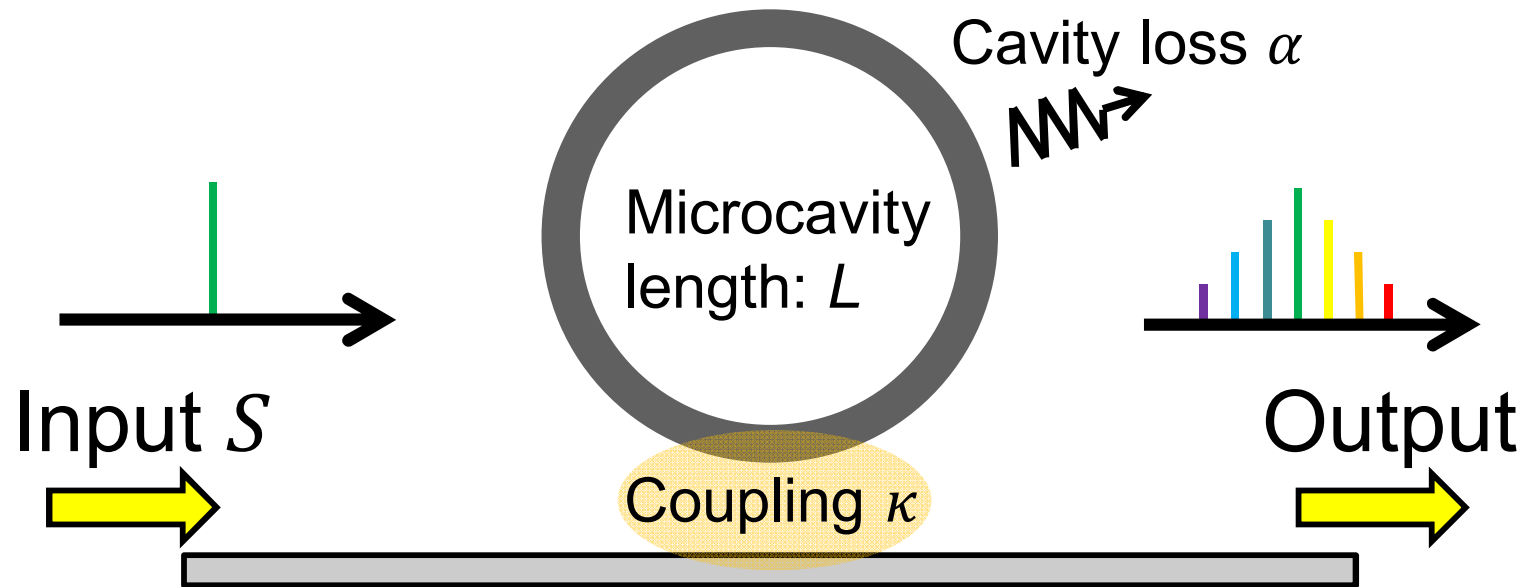
## ► Kerr comb generation



## ► SHG autocorrelation trace

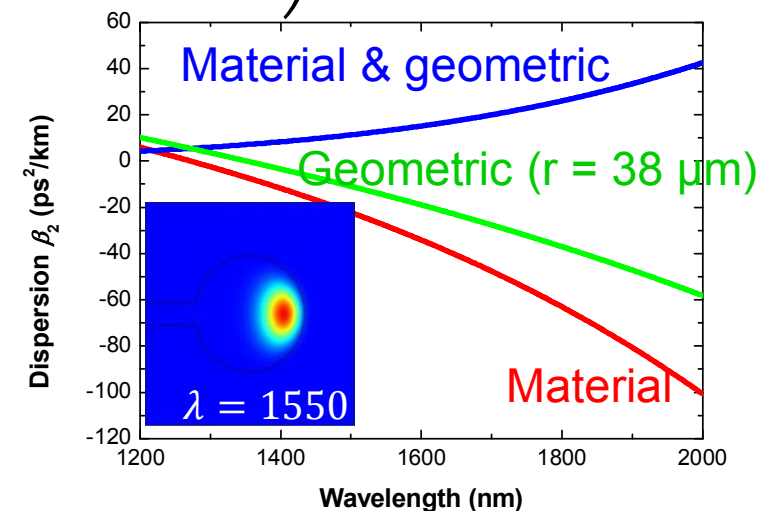


# Solving Lugiato-Lefever equation w/ split-step Fourier method



$$t_R \frac{\partial E}{\partial r} = \left( -\frac{\alpha}{2} - \frac{\kappa}{2} - i\delta_0 + iL \sum_{k \geq 2} \frac{\beta_k}{k!} \left( i \frac{\partial}{\partial T} \right)^k + i\gamma L |E|^2 \right) E + \sqrt{\kappa} S$$

$r$ : round trip number     $\beta$ : dispersion parameter  
 $t_R$ : round trip time     $\gamma$ : nonlinear parameter  
 $\delta_0$ : detuning of input

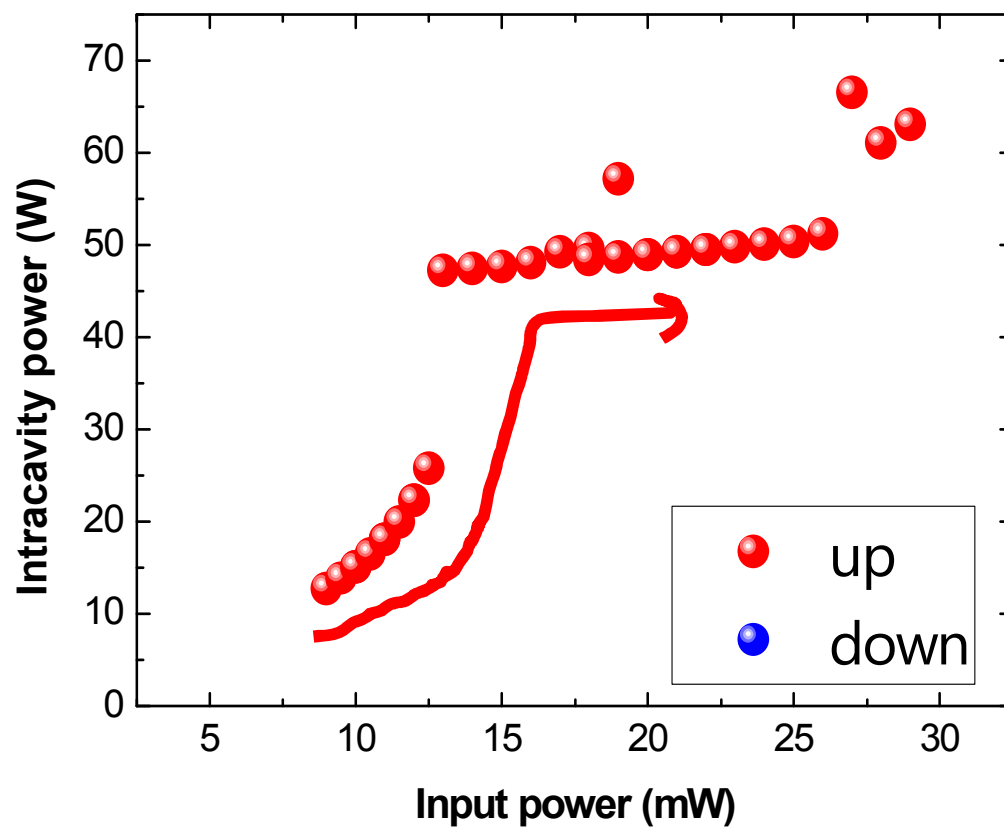


## Simulation: multi-FSR to fundamental mode-locking

T. Kato, *et. al.*, arXiv:1408.1204

$$Q_{\alpha} = 7.0 \times 10^6 \quad \Delta = 2 \text{ (detuning)}$$

$$Q_{\kappa} = 7.0 \times 10^6$$

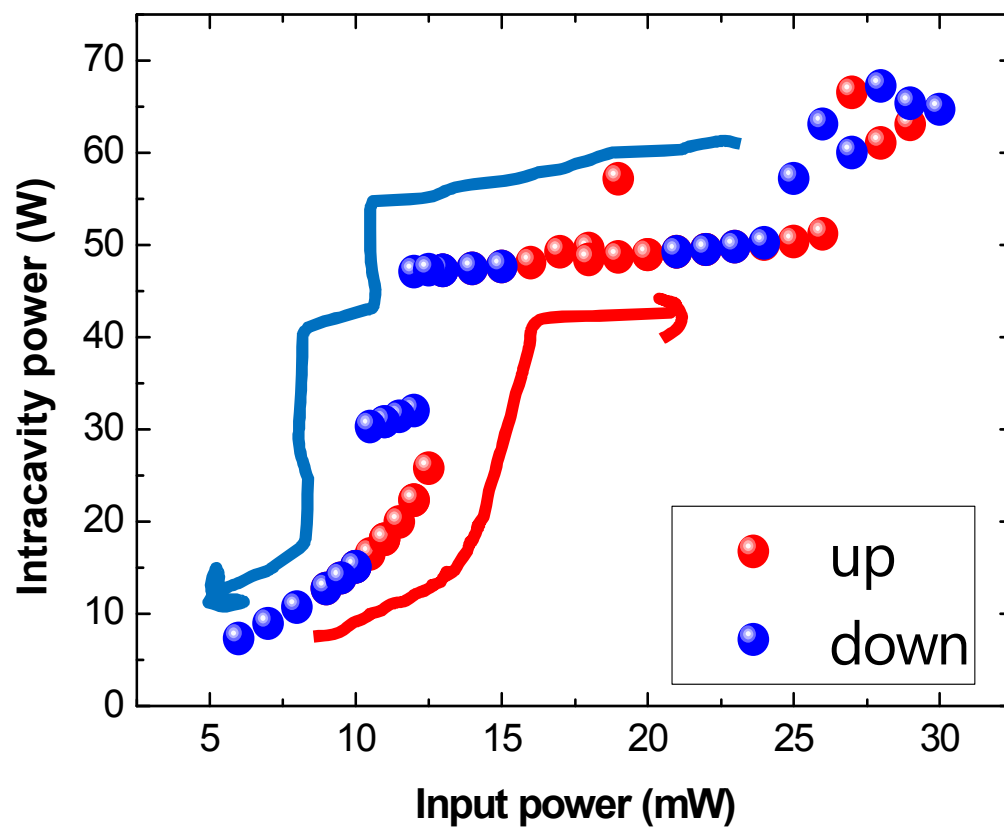


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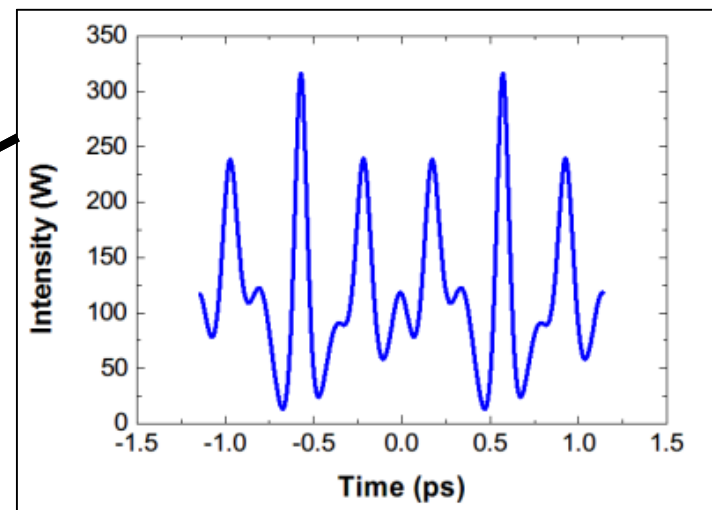
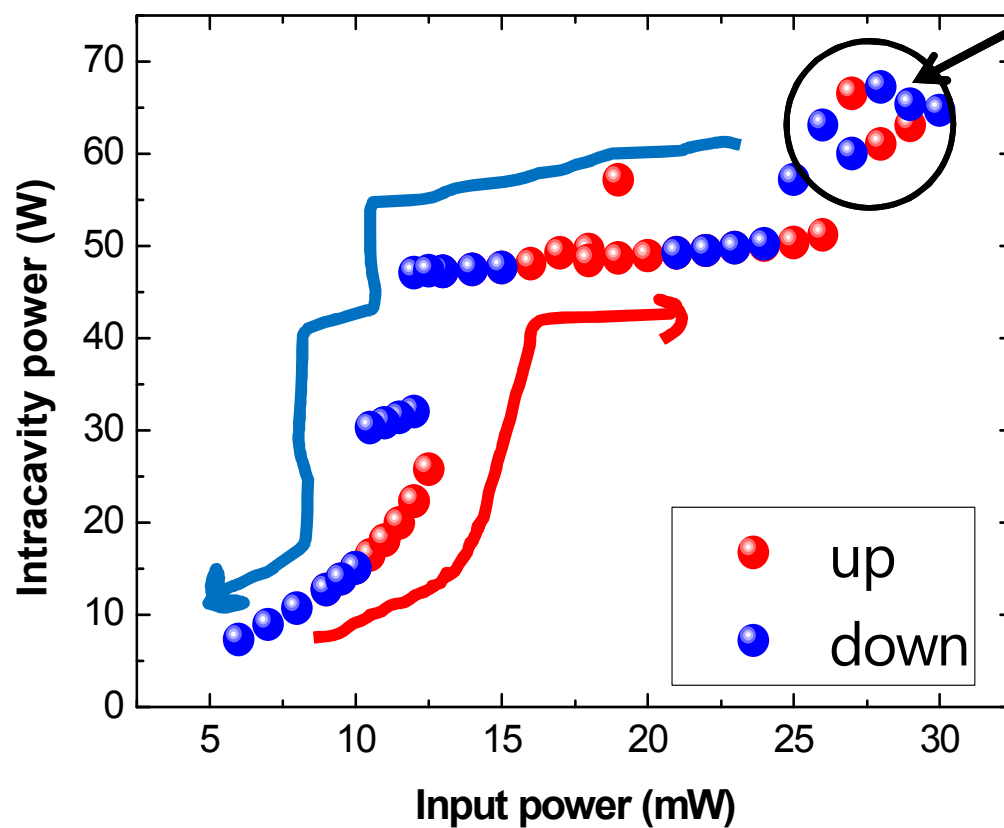


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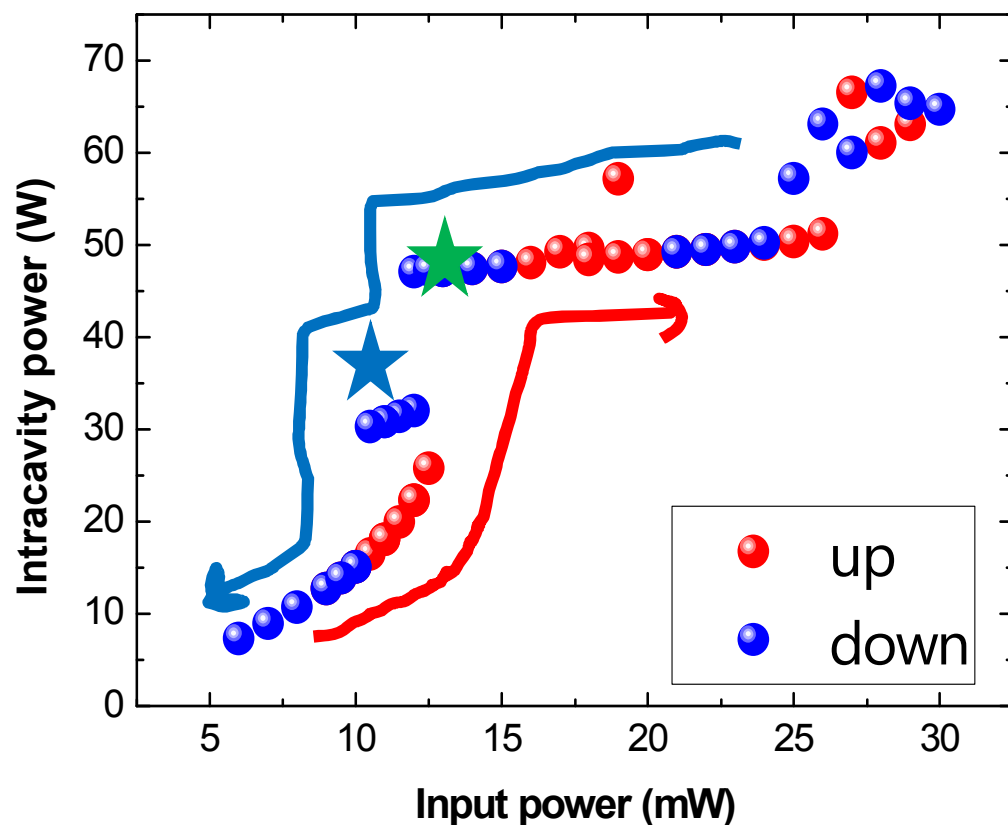


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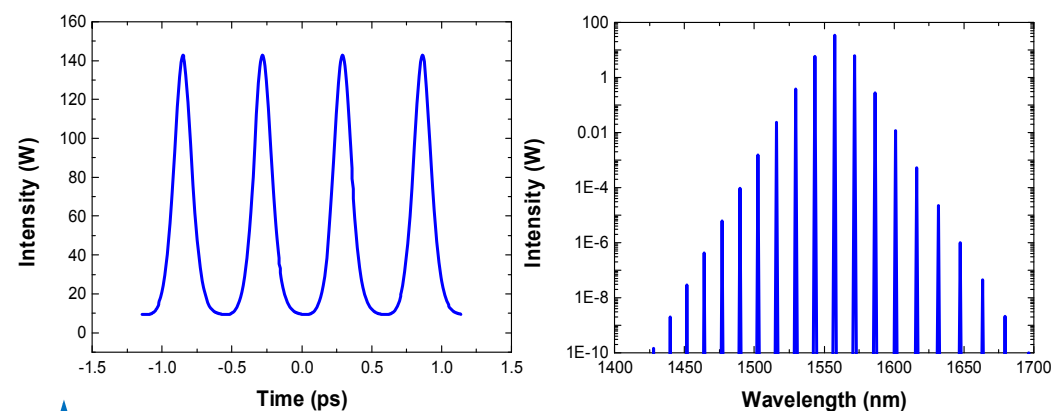
T. Kato, *et. al.*, arXiv:1408.1204

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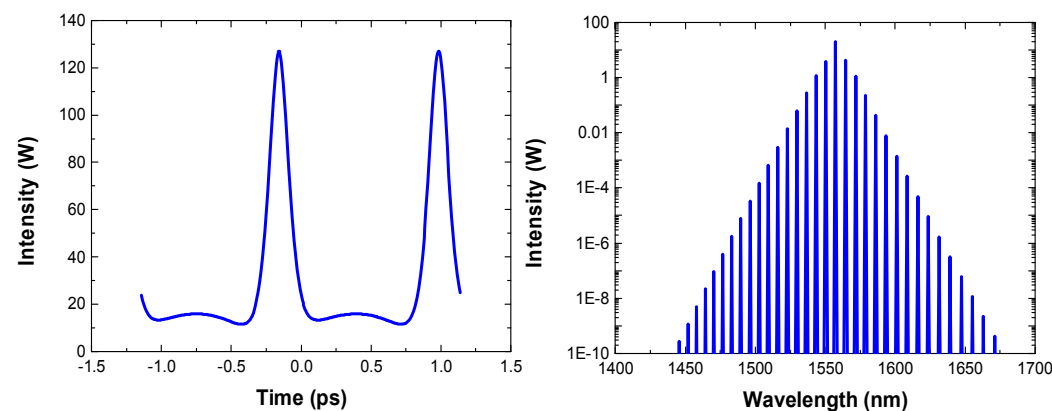
$$Q_{\kappa} = 7.0 \times 10^6$$



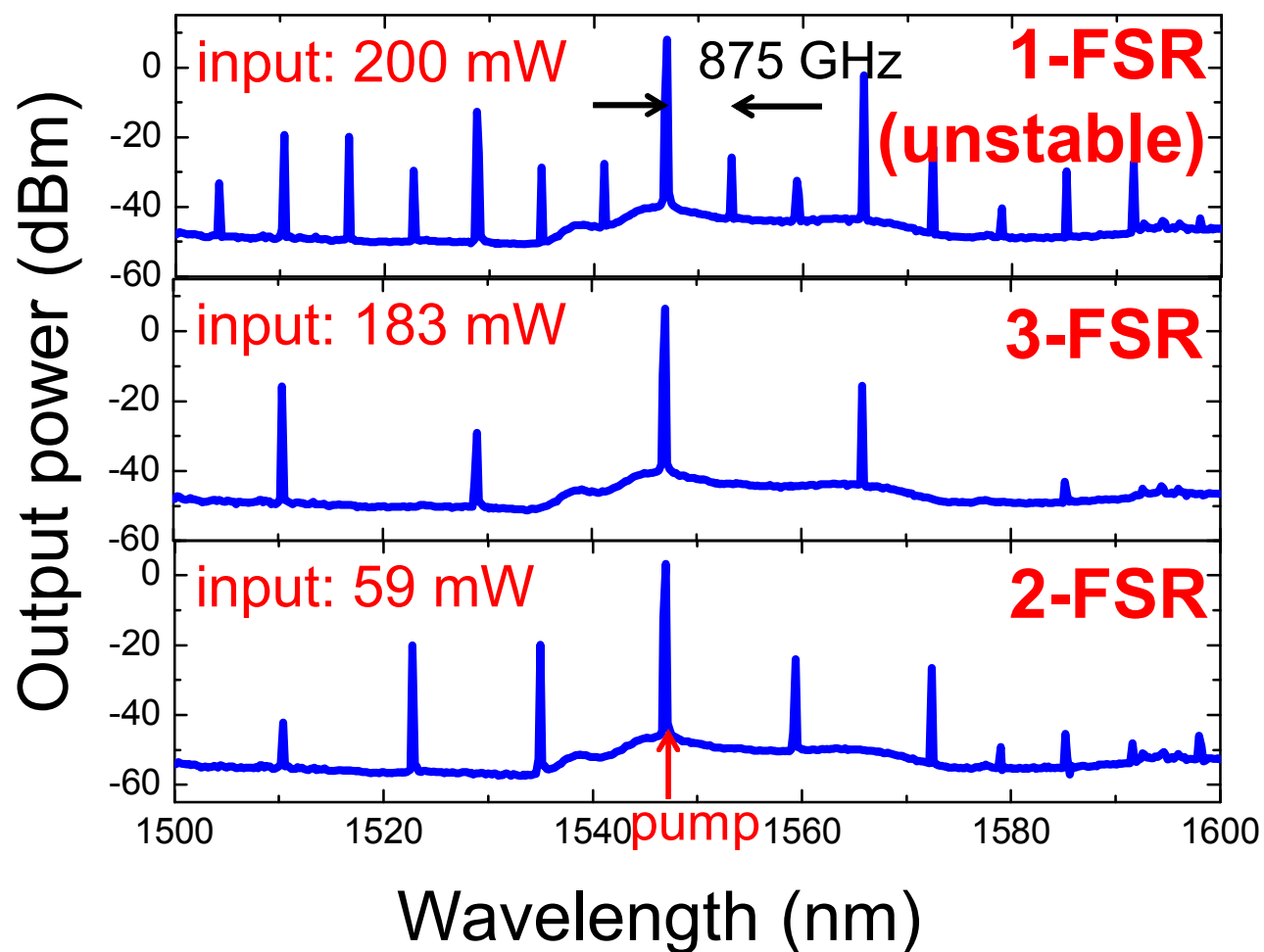
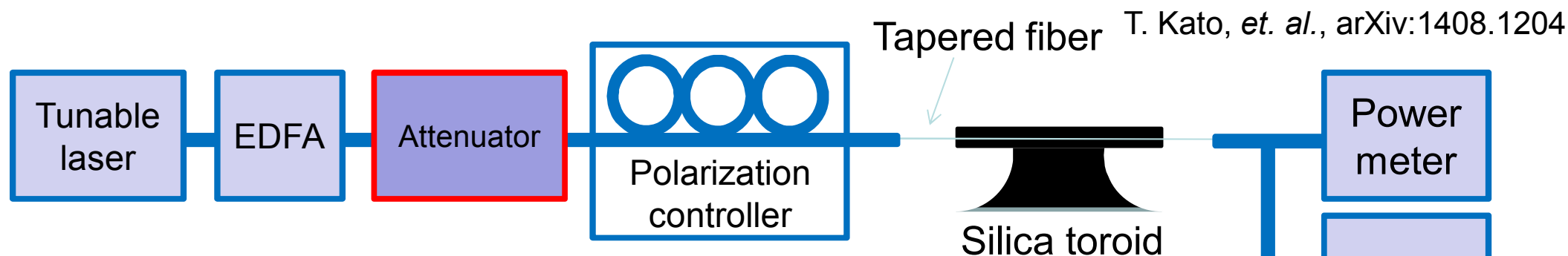
★ Harmonic mode locking(2-FSR)



★ Mode locking(1-FSR)



# Experiment: mode-locking by power control



## Experiment condition

Pump linewidth = 100 kHz  
 Pump power = 200 mW  
 Tapered fiber  $\phi \sim 1 \mu\text{m}$

$Q = 5 \times 10^6$   
 $V \sim 1000 \mu\text{m}^3$   
 Cavity FSR = 875 GHz

# Considering Raman effect



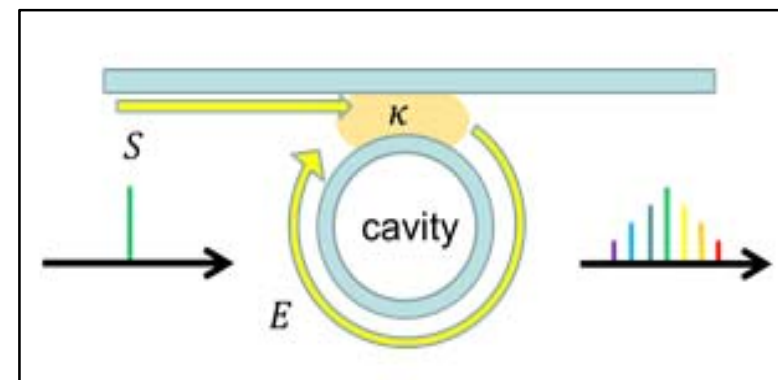
$$t_R \frac{\partial E}{\partial t} = \left[ -\alpha - \kappa - i\delta_0 + iL \sum_{k \geq 2} \frac{\beta_k}{k!} \left( i \frac{\partial}{\partial \tau} \right)^k + N \right] E + \sqrt{\theta} E_{in}$$

$$N = i\gamma L \left( 1 + \frac{i}{\omega_0} \frac{\partial}{\partial t} \right) \left( E \int_{-\infty}^{\infty} R(t') |E(t - t')|^2 dt' \right)$$

$$R(t) = (1 - f_R)\delta(t) + f_R h_R(t)$$

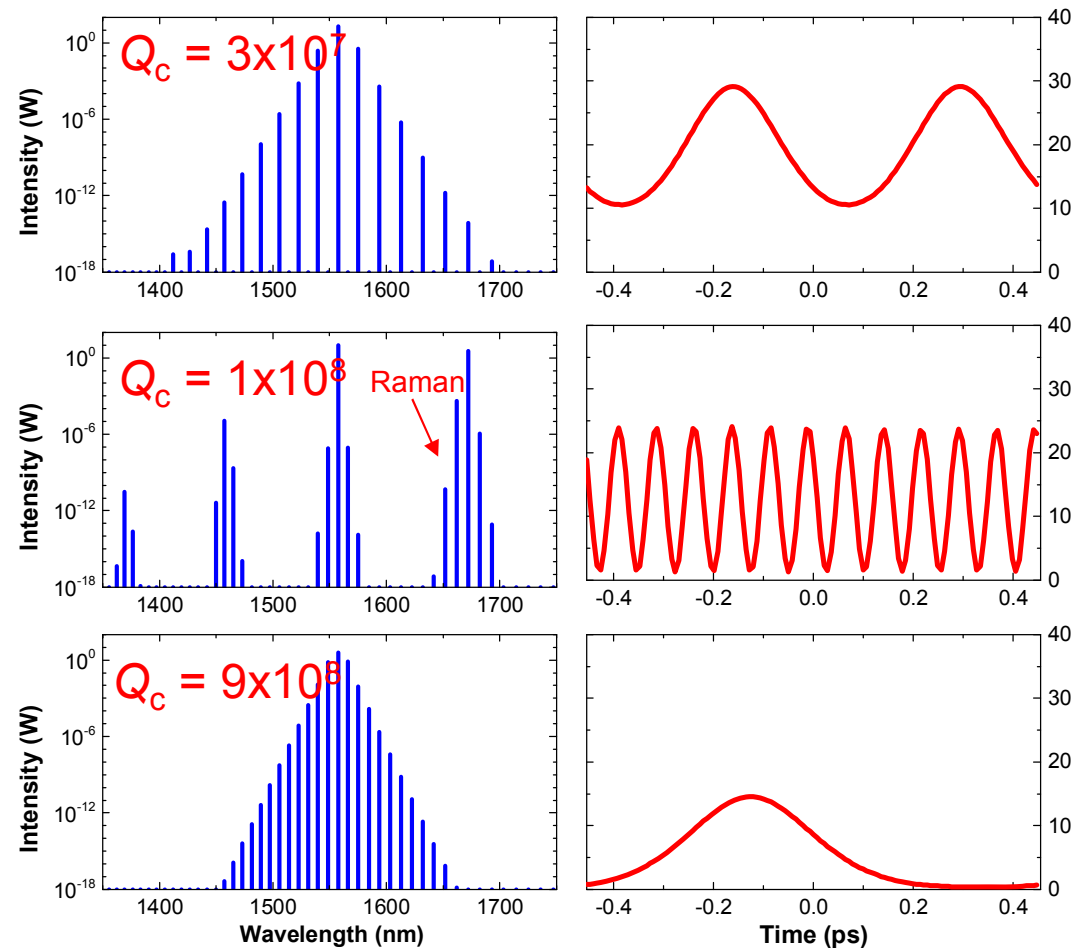
$$h_R(t) = \left( \frac{\tau_1^2 + \tau_2^2}{\tau_1 \tau_2^2} \right) \exp\left(-\frac{t}{\tau_2}\right) \sin\left(\frac{t}{\tau_1}\right)$$

$S$  : Input power                       $\kappa$ : coupling coefficient  
 $r$ : round trip number                 $\beta$ : dispersion parameter  
 $t_R$ : round trip time                  $\gamma$ : nonlinear parameter  
 $\delta_0$ : detuning of input              $f_R$ : contribution of Raman

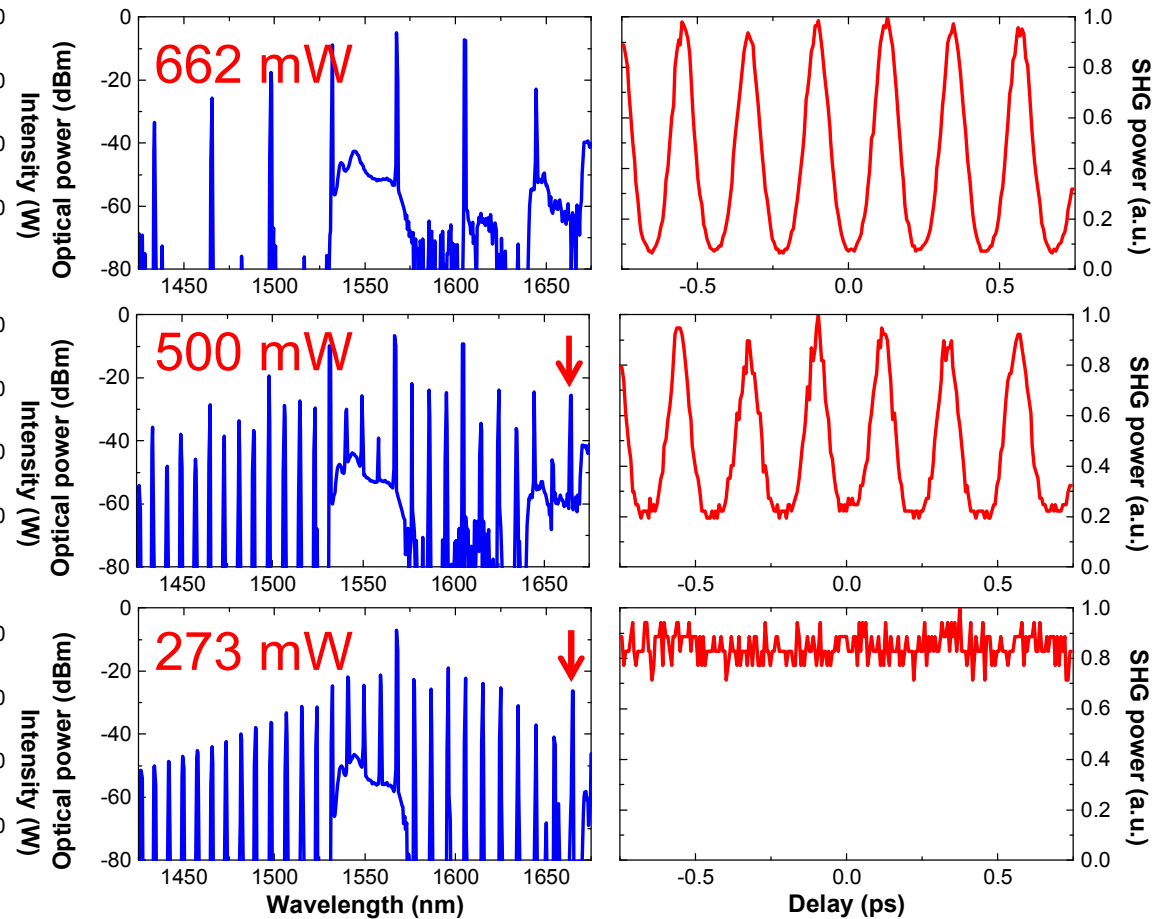


Transition between multi-FSR mode locking: Effect of Raman 

## ► Calculation (coupling)

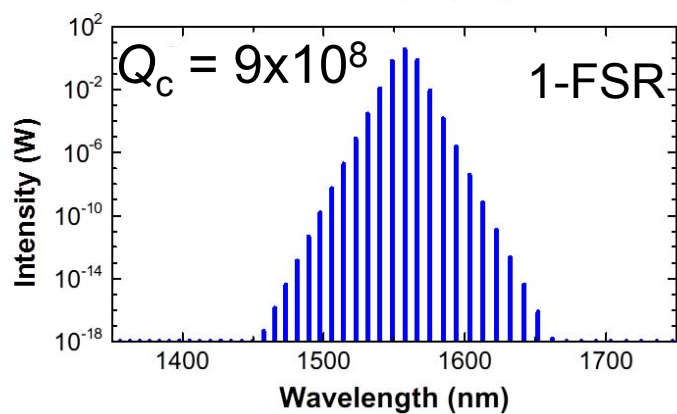
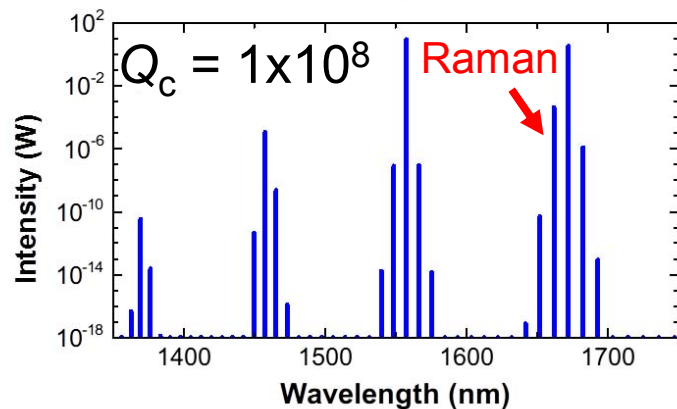
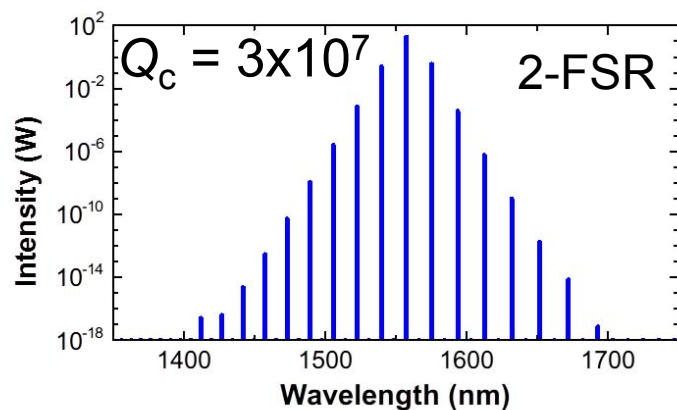


## ► Experiment (power control)

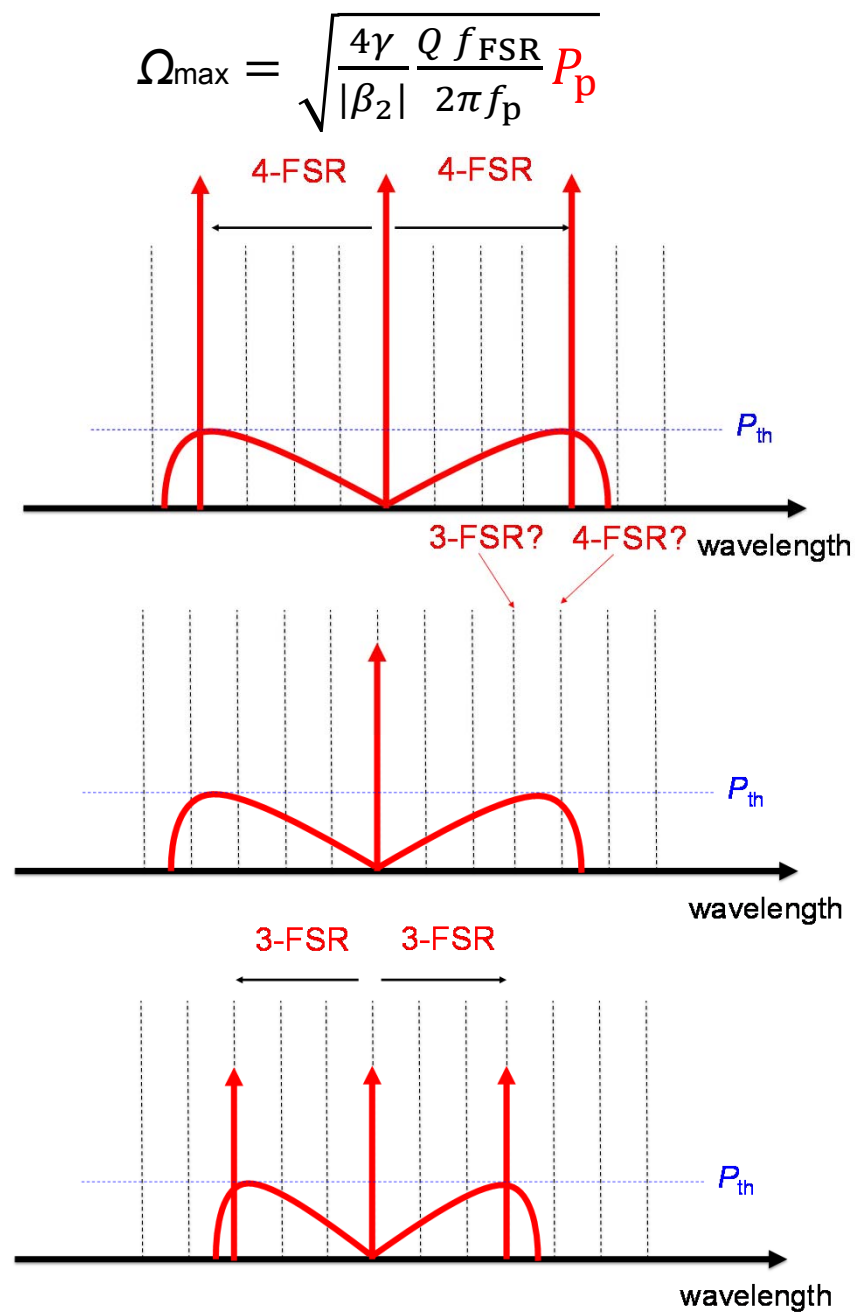


Transition between multi-FSR mode locking: Effect of Raman 

$$\Omega_{\max} = \sqrt{\frac{4\gamma}{|\beta_2|} \frac{Q f_{\text{FSR}}}{2\pi f_p} P_p}$$



Decreasing pumping power



# Summary & Future prospect



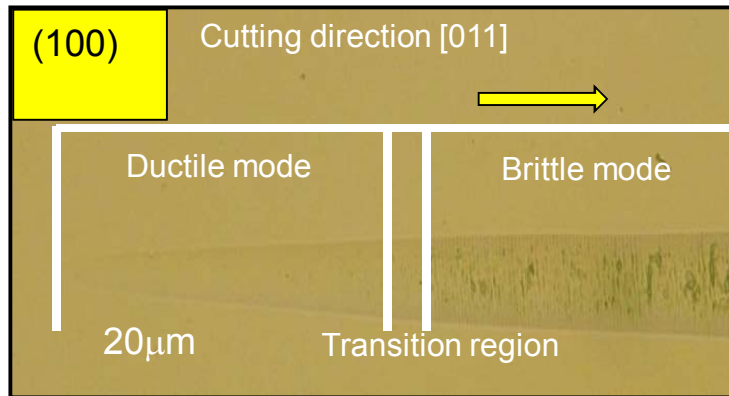
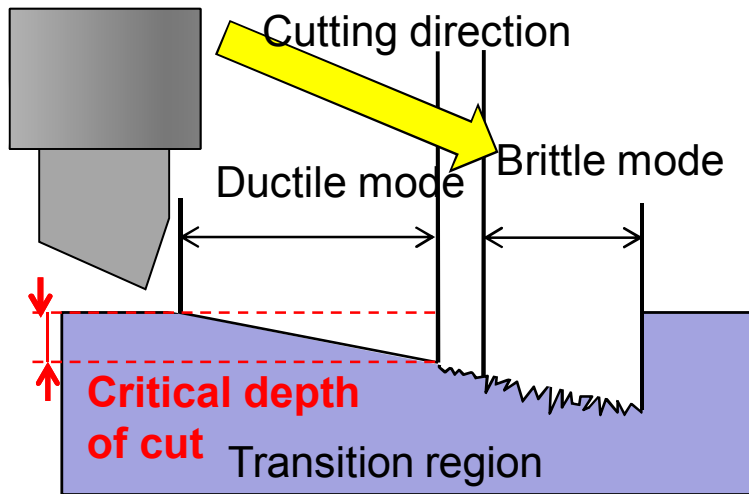
- ✓ Optical Kerr switch at lowest power demonstrated
- ✓ Kerr comb at 850-GHz spacing is generated
- ✓ 2-FSR mode locking is achieved with 60-mW power
- ✓ We found decreasing the input is essential to obtain mode locking



# Fabrication of CaF<sub>2</sub> WGM cavity w/ cutting

## ► Precise machining process

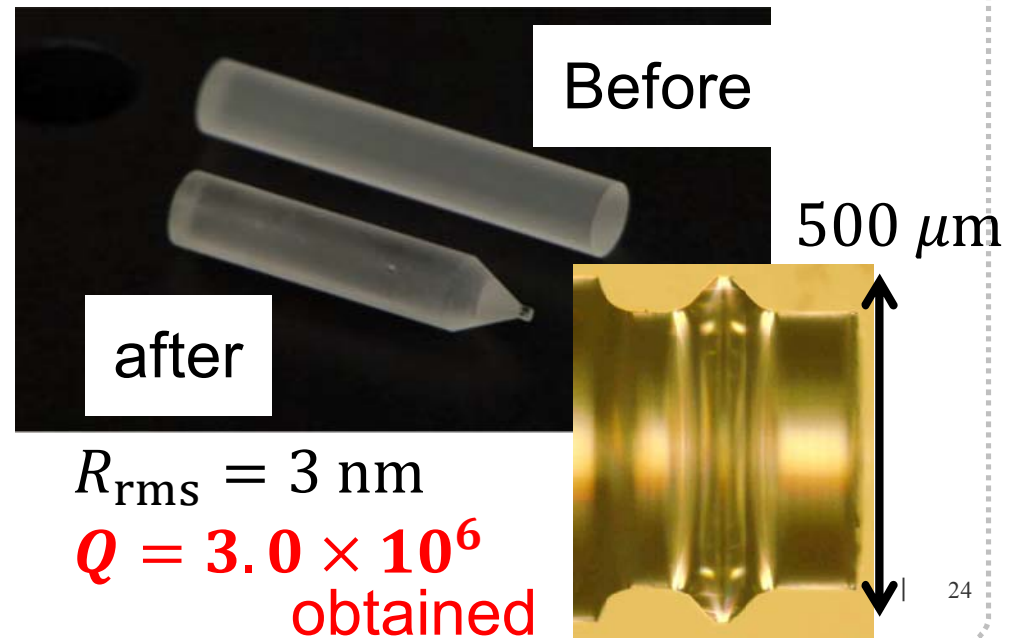
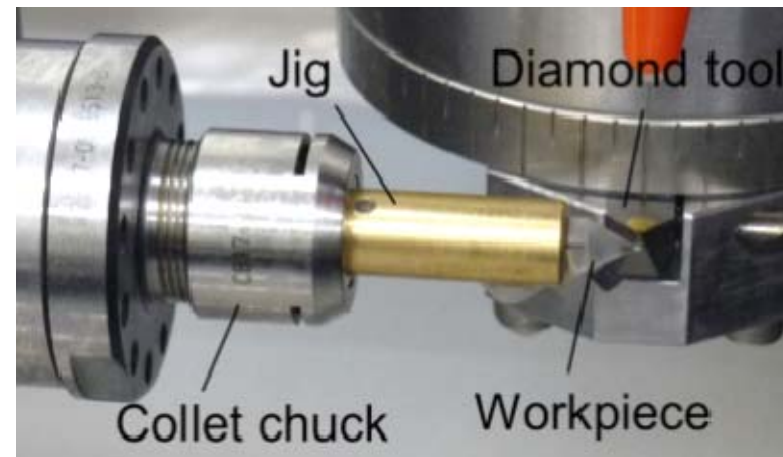
Y. Mizumoto, *et al.*, *Procedia Eng.* **19**, 264 (2011).



► CaF<sub>2</sub> can be smoothly cut in ductile mode cutting

## ► Lathe cutting

S. Azami, *et al.* *Procedica CIRP* **13**, 225 (2014).

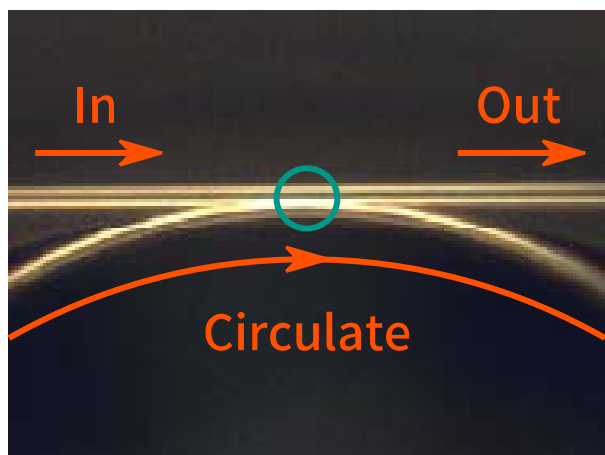




# Optical measurement & Surface roughness



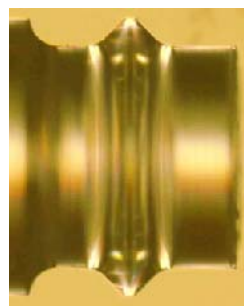
## Q measurement



### Parameters:

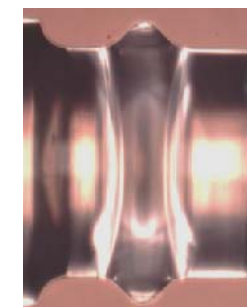
- Fiber diameter: 3~5  $\mu\text{m}$
- Input power: 1 mW
- Scan speed: 1 nm/s

Before polishing  $\longrightarrow$  After polishing

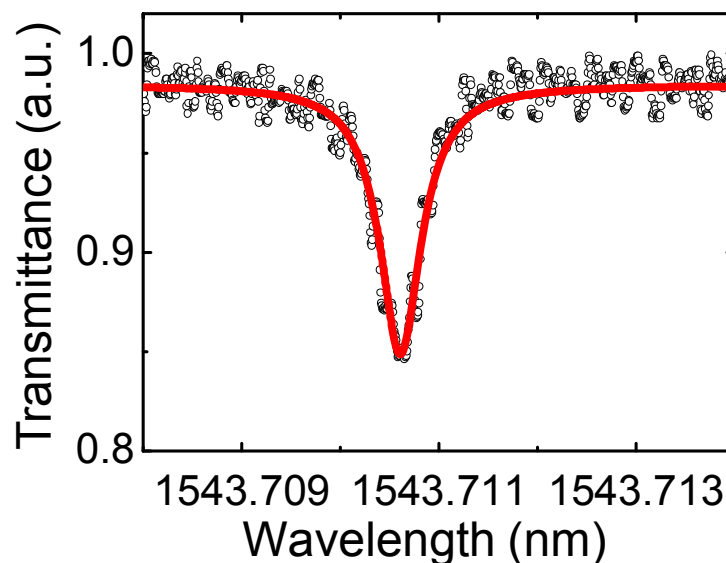


$R_{\text{rms}} = 3 \text{ nm}$

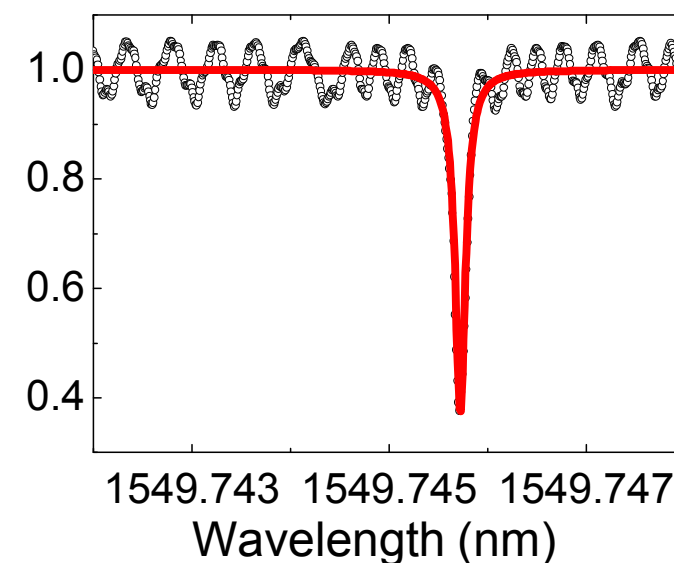
Unchanged



$R_{\text{rms}} = 3 \text{ nm}$



$Q = 3.0 \times 10^6$



$Q = 1.2 \times 10^7$

Increased

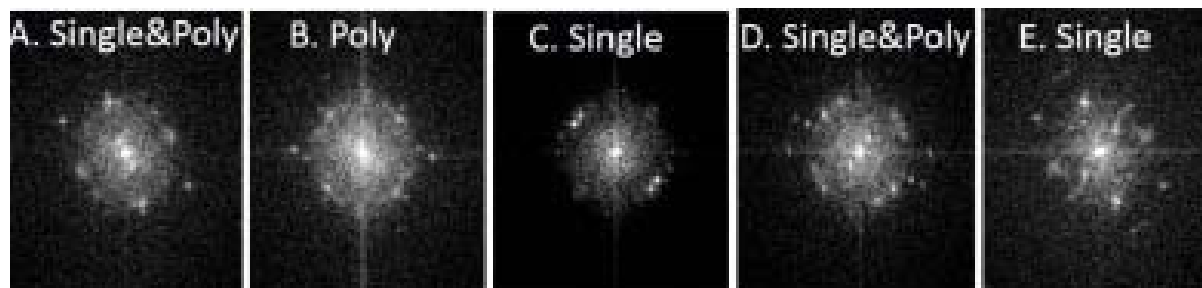
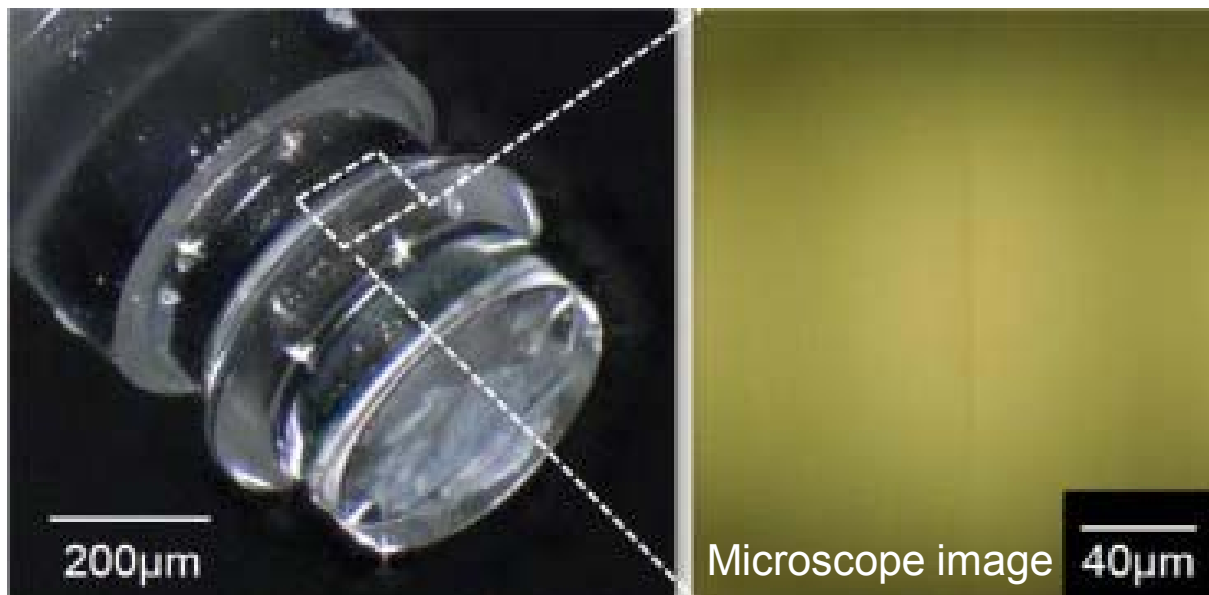


# Surface: Dislocation loops

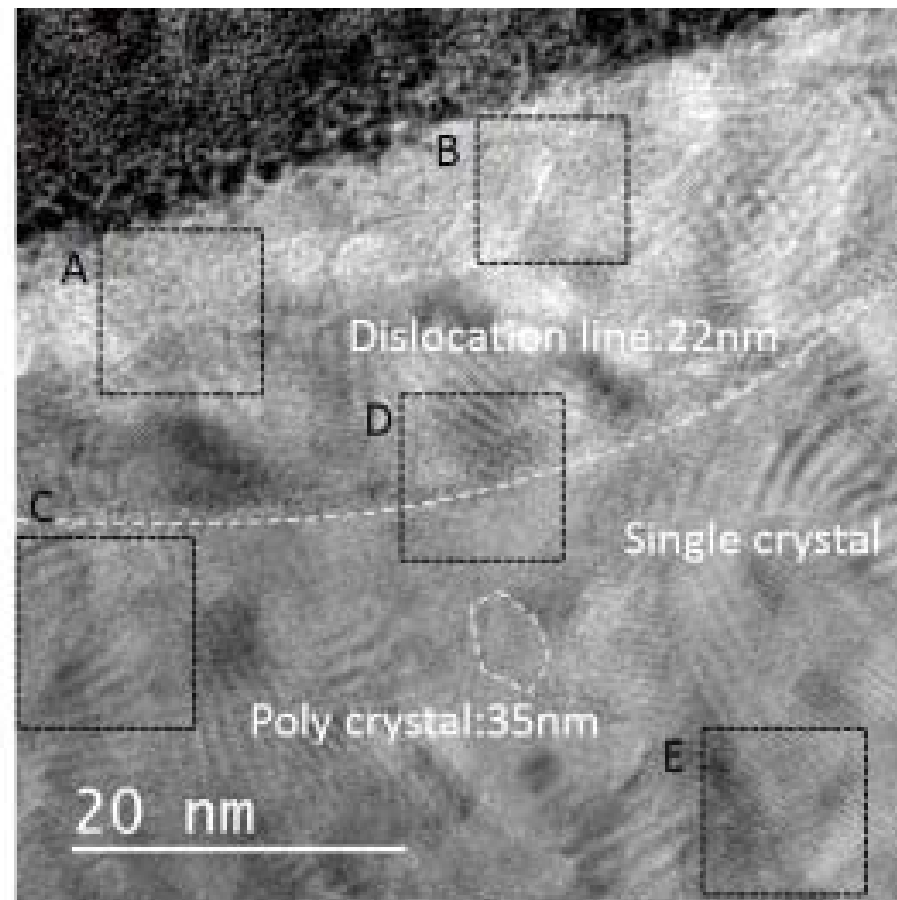


Y. Kakinuma, *et al.*, CIRP Annuals (2015) in press.

## TEM image



Diffraction images



**Polycrystalline layer must be removed**



# Acknowledgement

## ▶ The team



## ▶ Collaborators

Prof. Y. Kakinuma (Keio Univ.)

Dr. M. Notomi (NTT)

Dr. E. Kuramochi (NTT)

## ▶ Support

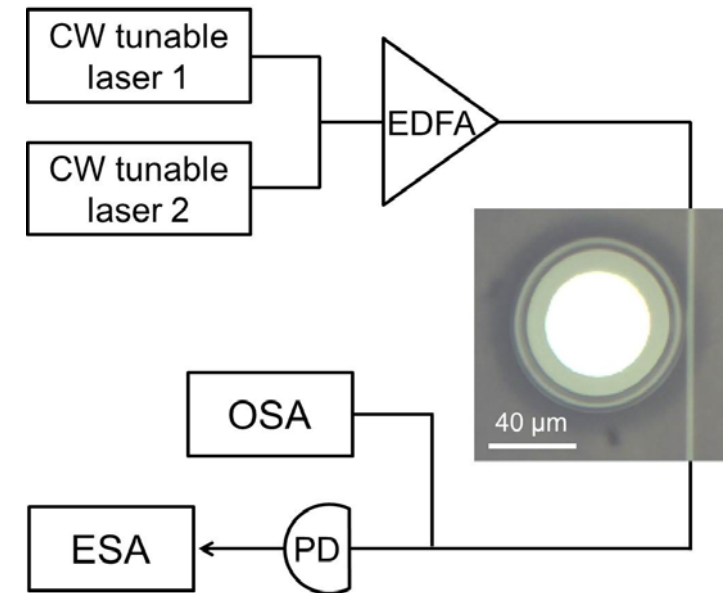
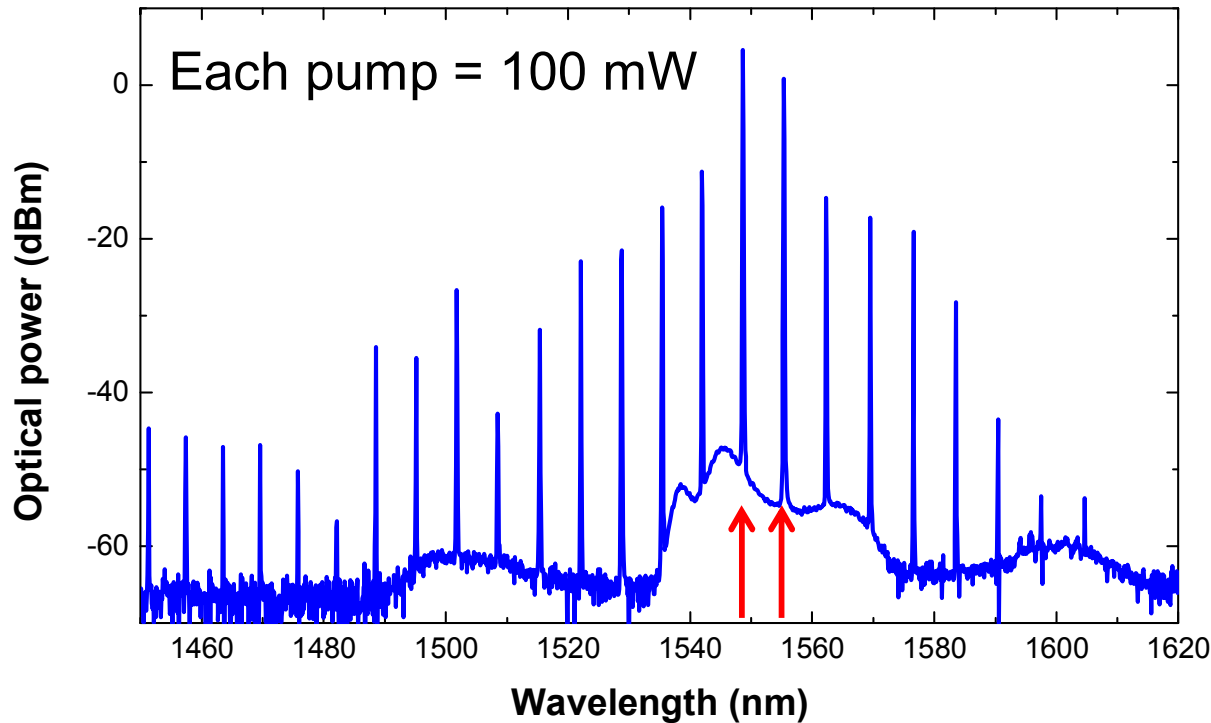


Ministry of Education, Culture, Sports, Science, and Technology (MEXT),  
Japan, KAKEN #15H05429



Strategic Information and Communications R&D Promotion Programme  
(SCOPE), from the Ministry of Internal Affairs and Communications

# Kerr comb generation with toroid microcavity (Dual pump)



► Controllable mode spacing: generating Type1 (low noise) comb intentionally

